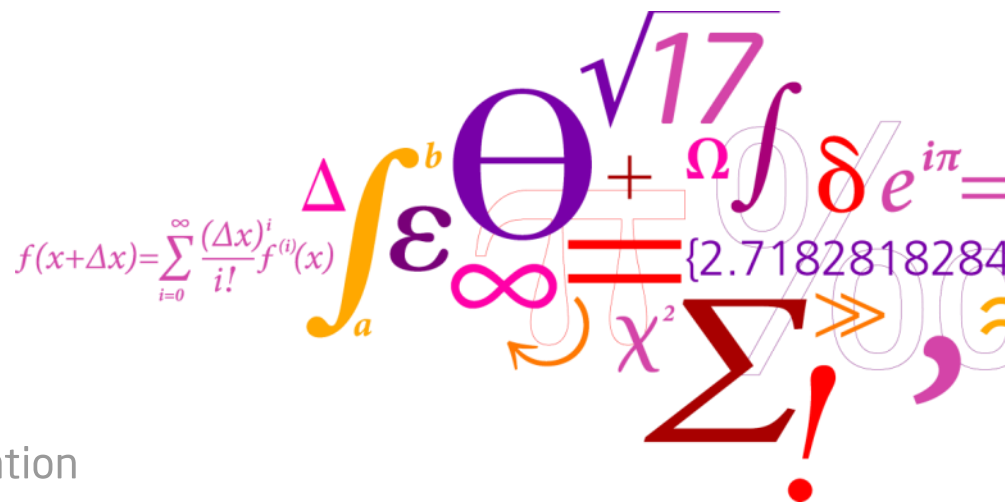


Laser Micromachining Tool 7.013

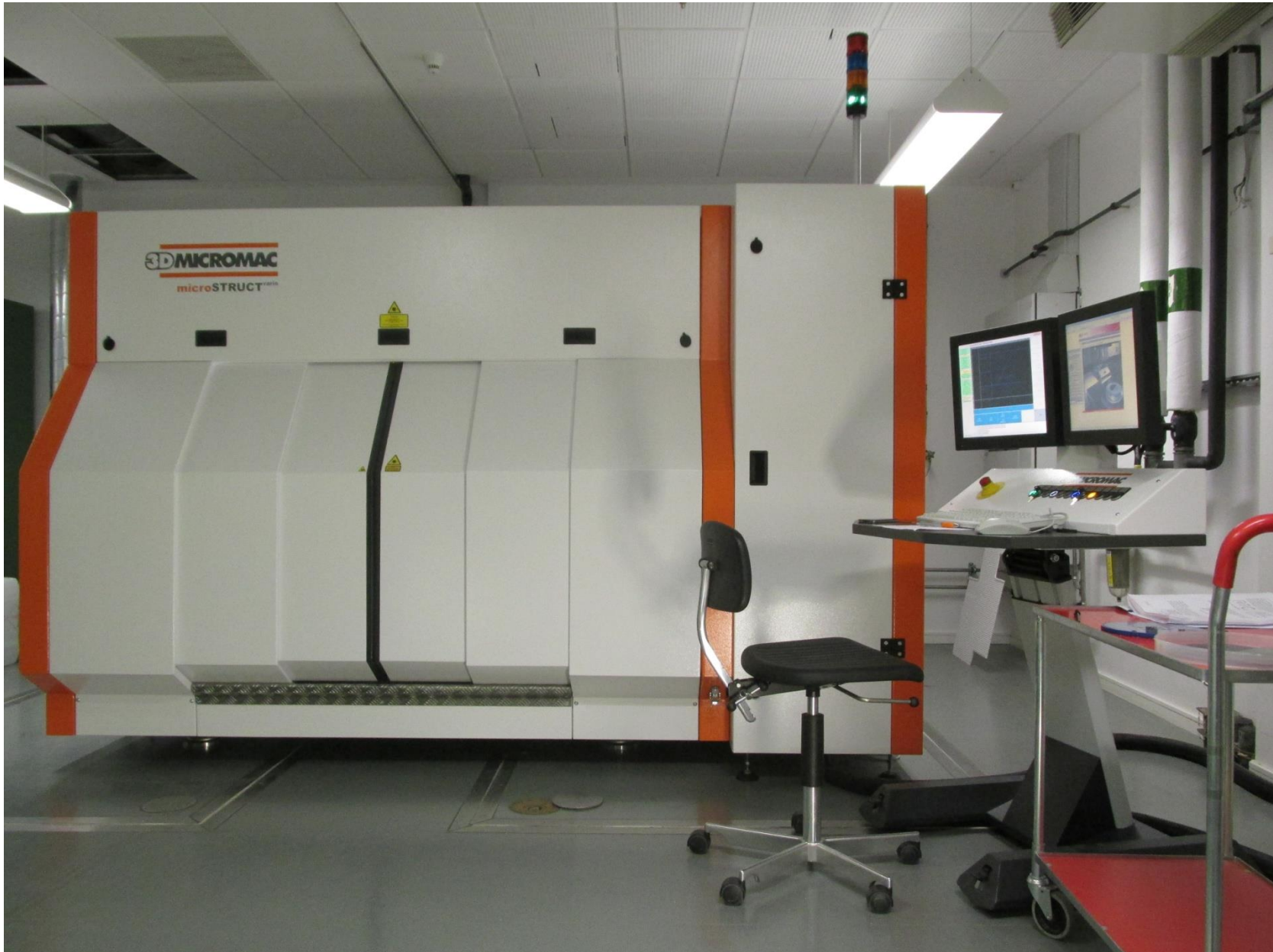
Chantal, Frederik, Helle, Jesper, Rune, Tine and Anders

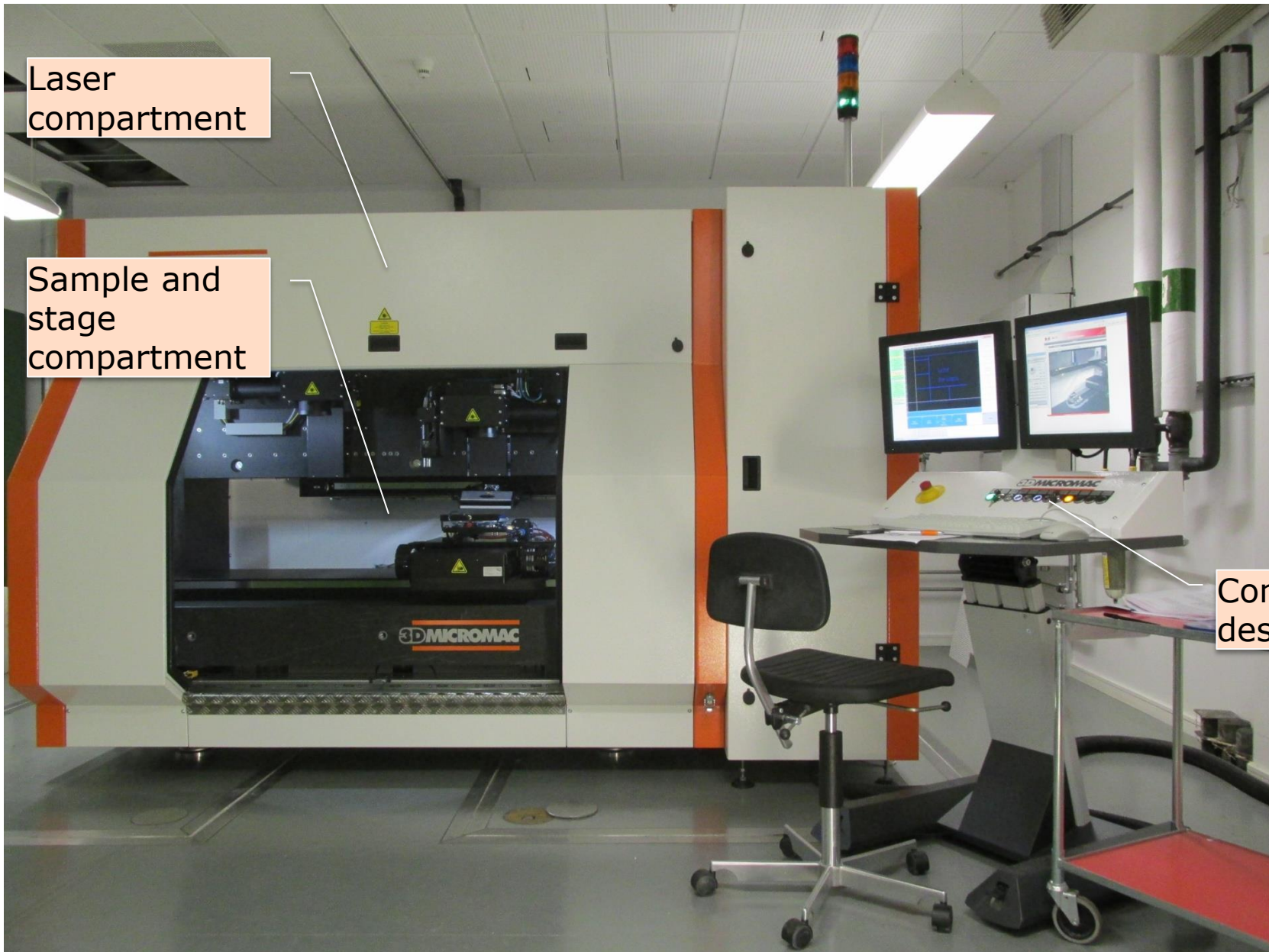


Meet 6 tonnes of german engineering

THE MACHINE







Laser
compartment

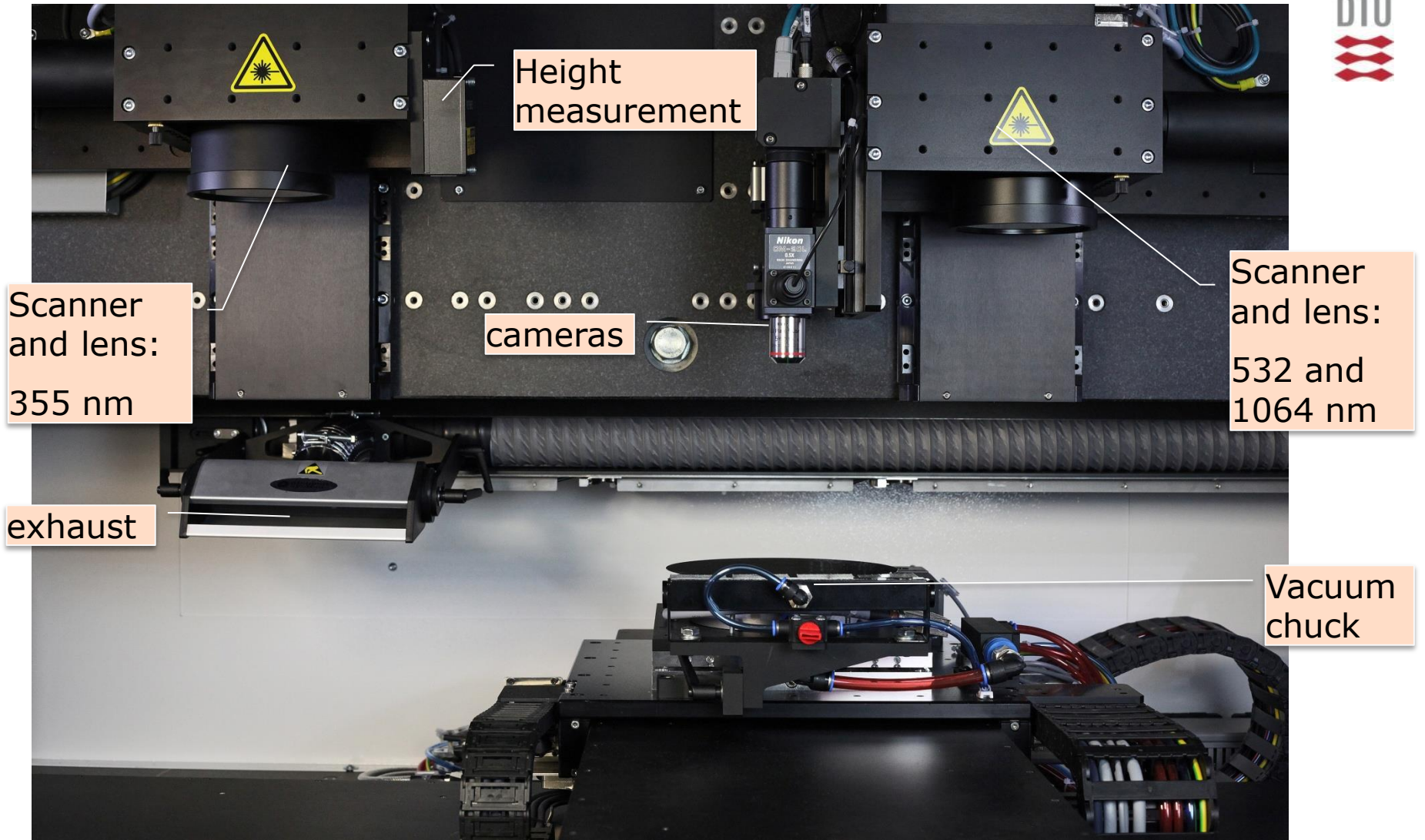
Sample and
stage
compartment

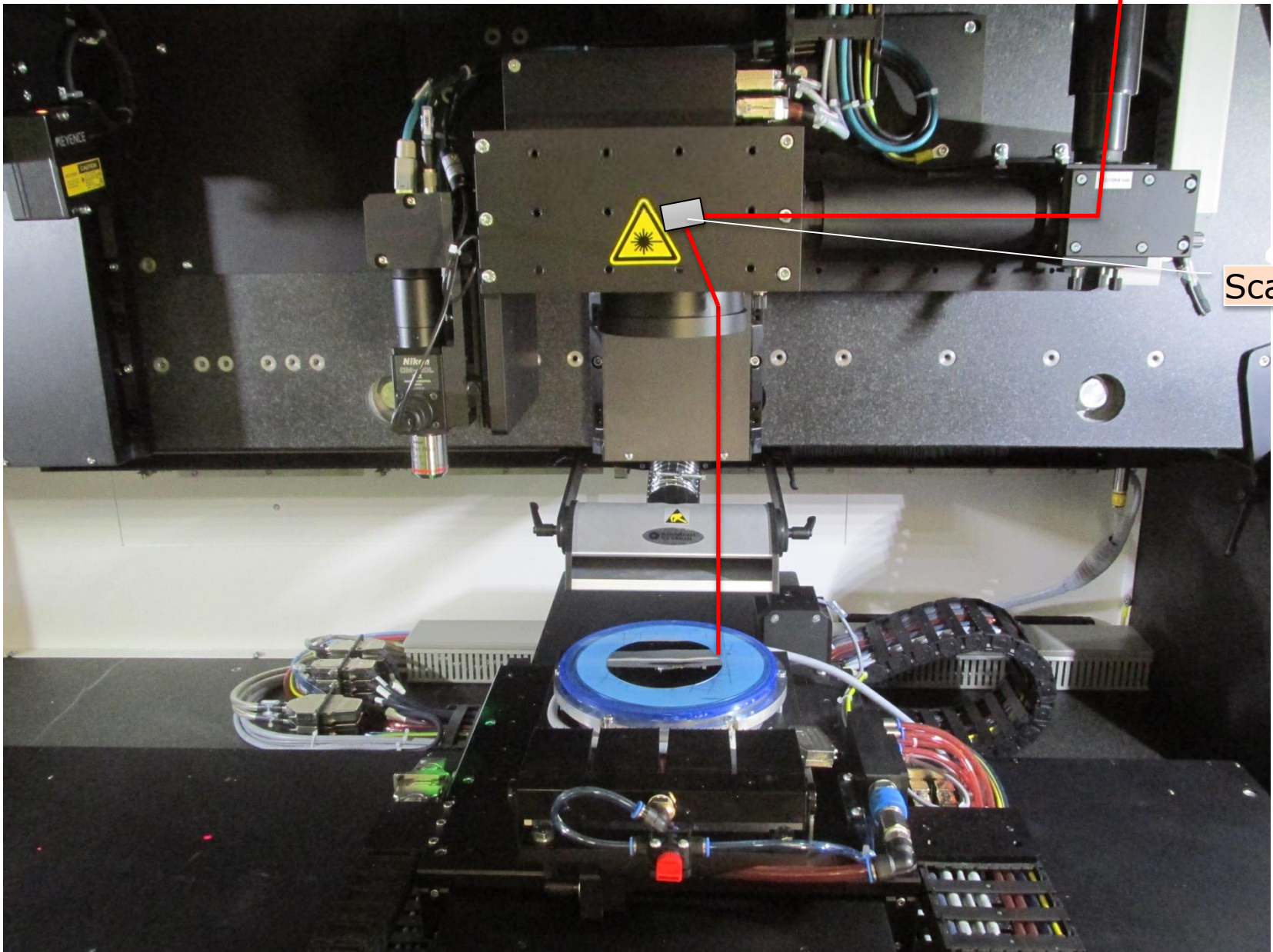
Control
desk



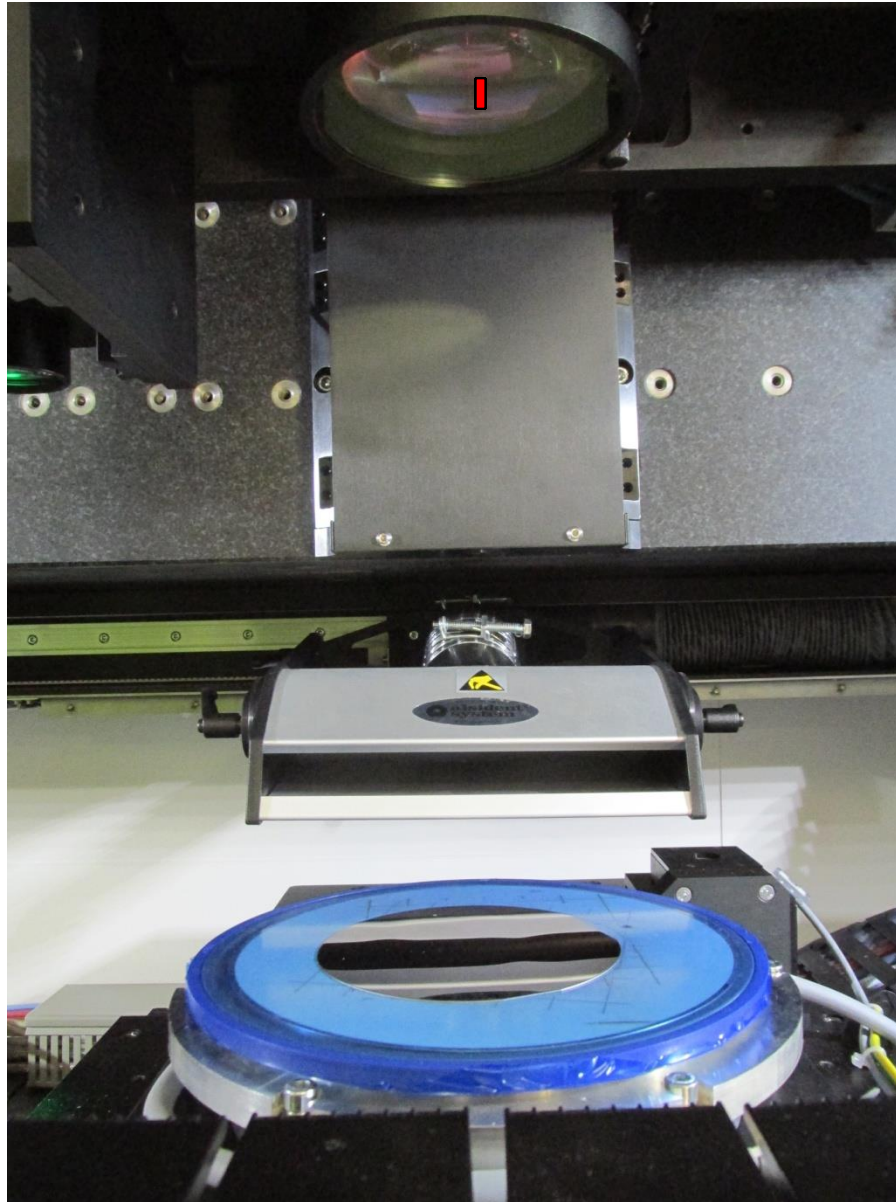
Scanner
and lens

sample
xy-stage





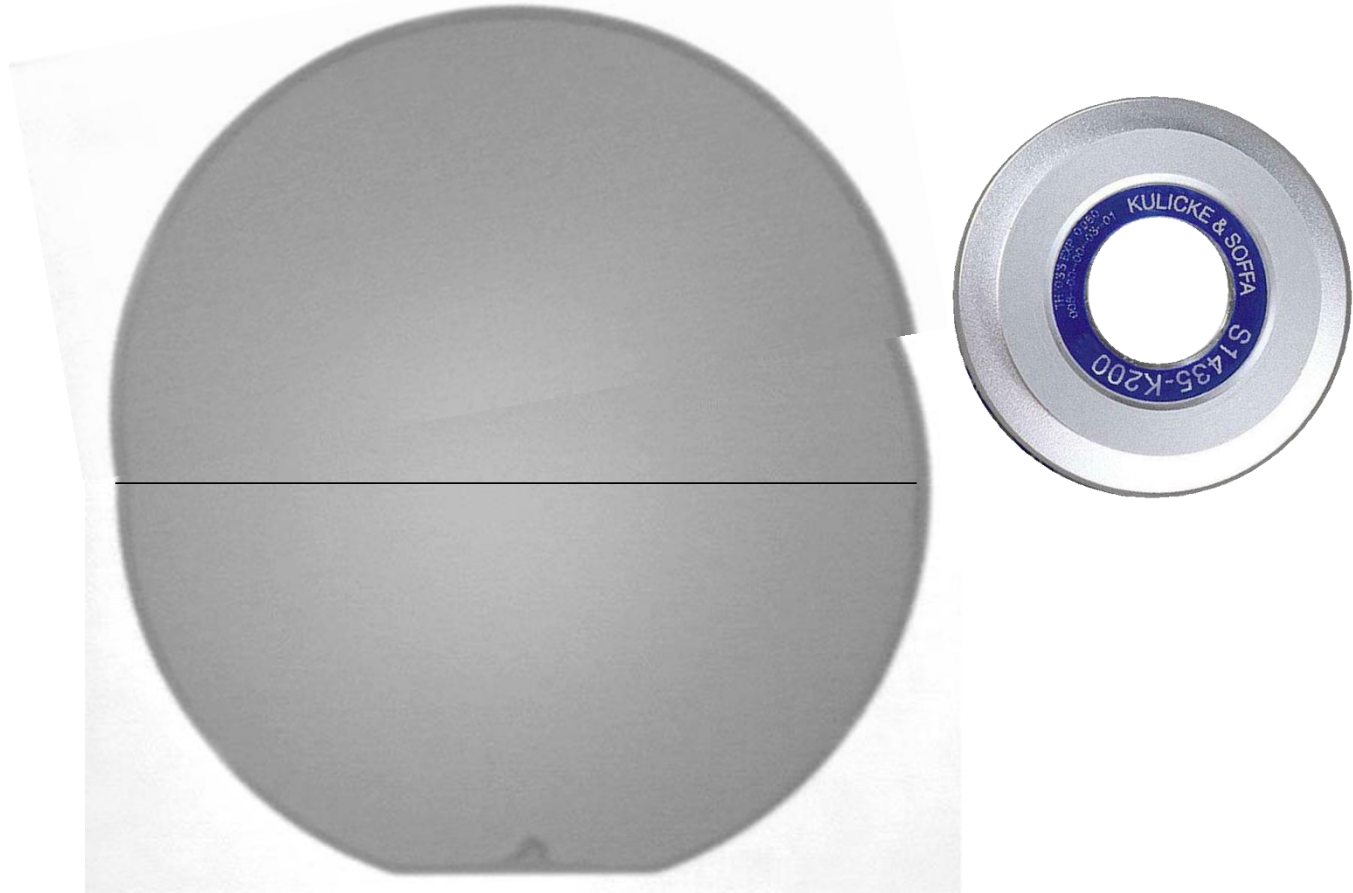
Scanner



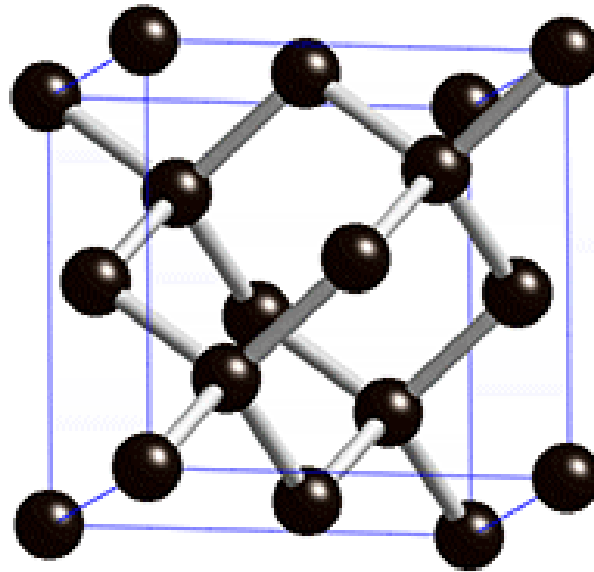
Short pulse laser light and solid materials

THE PHYSICS

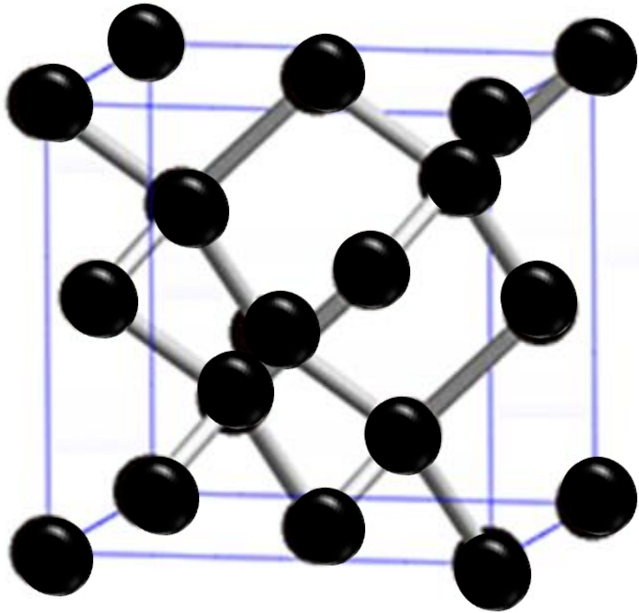
For example: A Silicon Wafer



A Silicon Wafer: Pure Silicon ...and its Crystal Structure:



Physical specifications of pure Silicon:



Melting Point: 1700 K

Boiling Point: 3500 K

Heat of Evaporation: 30 kJ/cm³

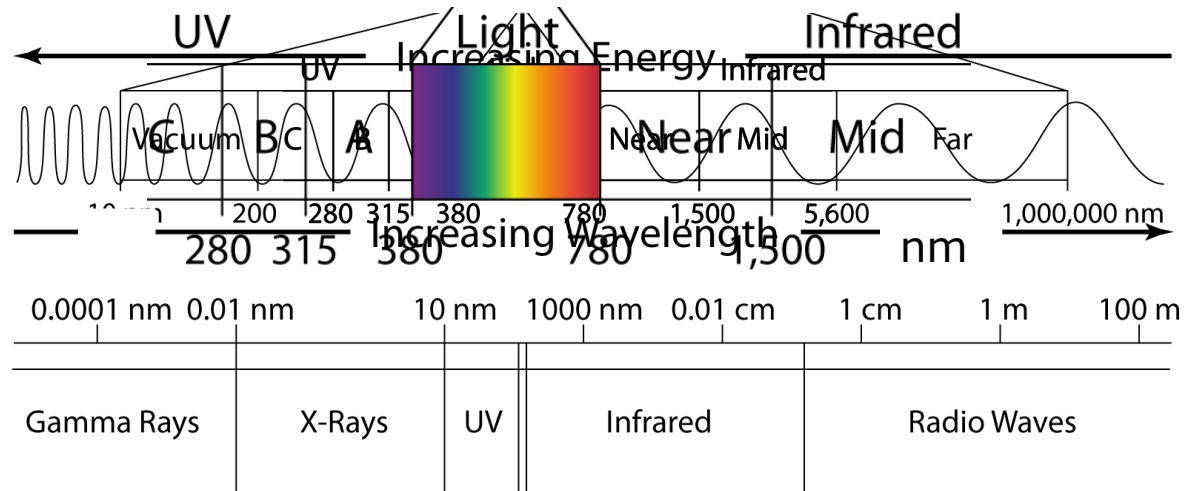
→Energy per chemical bond:

$$3 \cdot 10^{-19} \text{ J} = 2 \text{ eV}$$

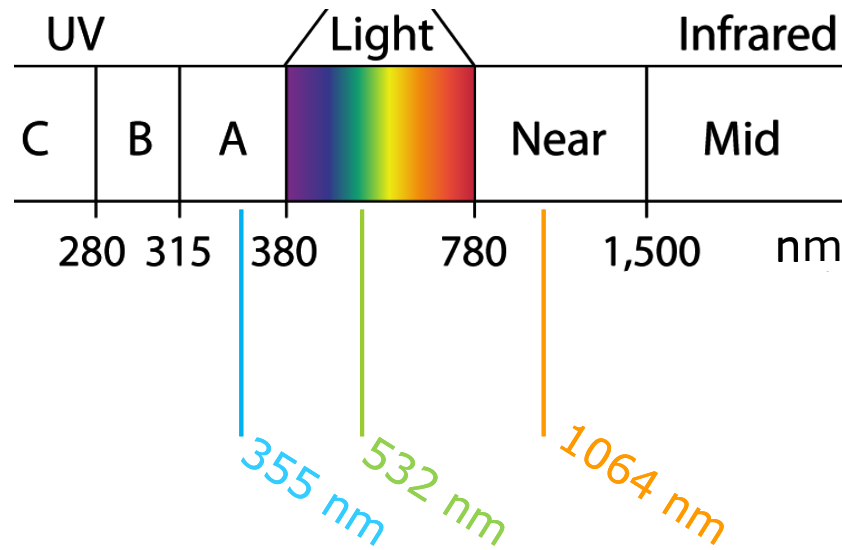
→Energy for evaporating a volume of 1 μm³:

$$3 \cdot 10^{-8} \text{ J} = 1 \cdot 10^{11} \cdot 2 \text{ eV}$$

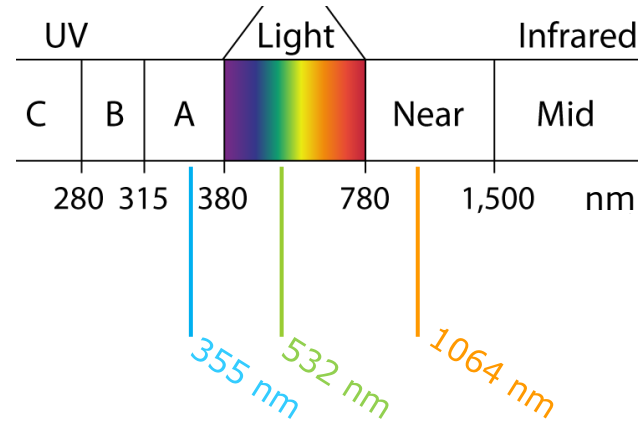
Laserlight



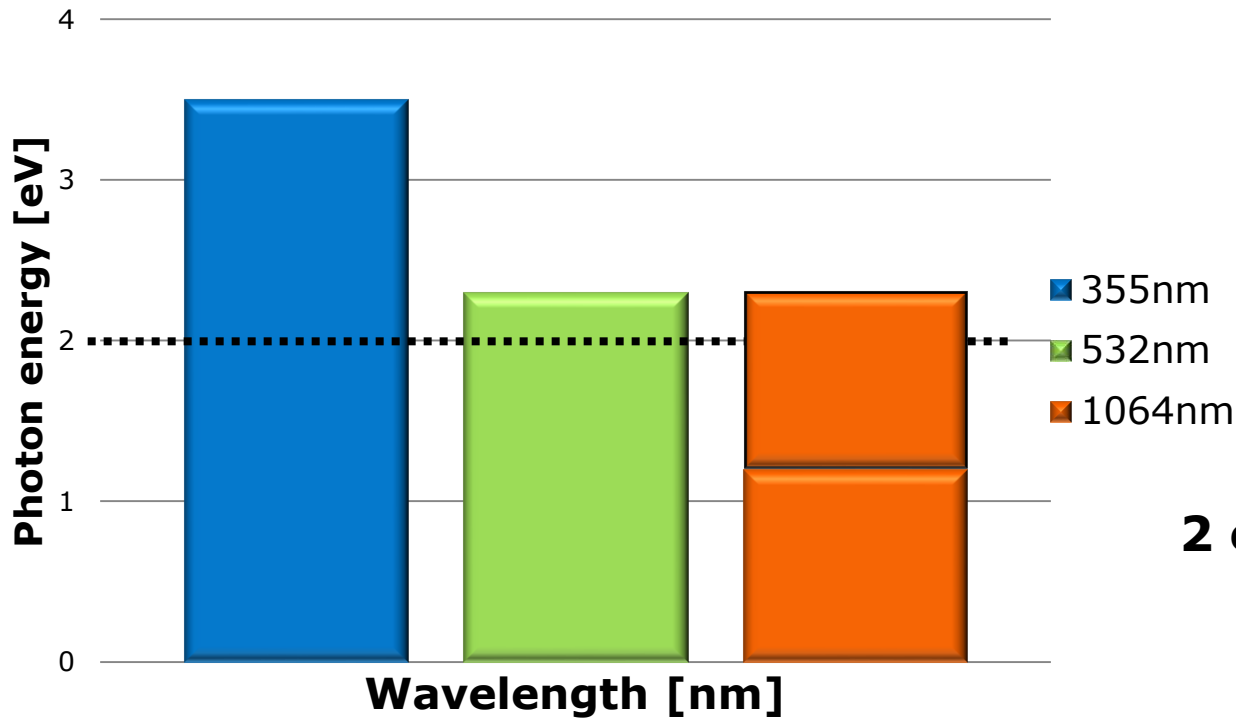
Laserlight



Laserlight

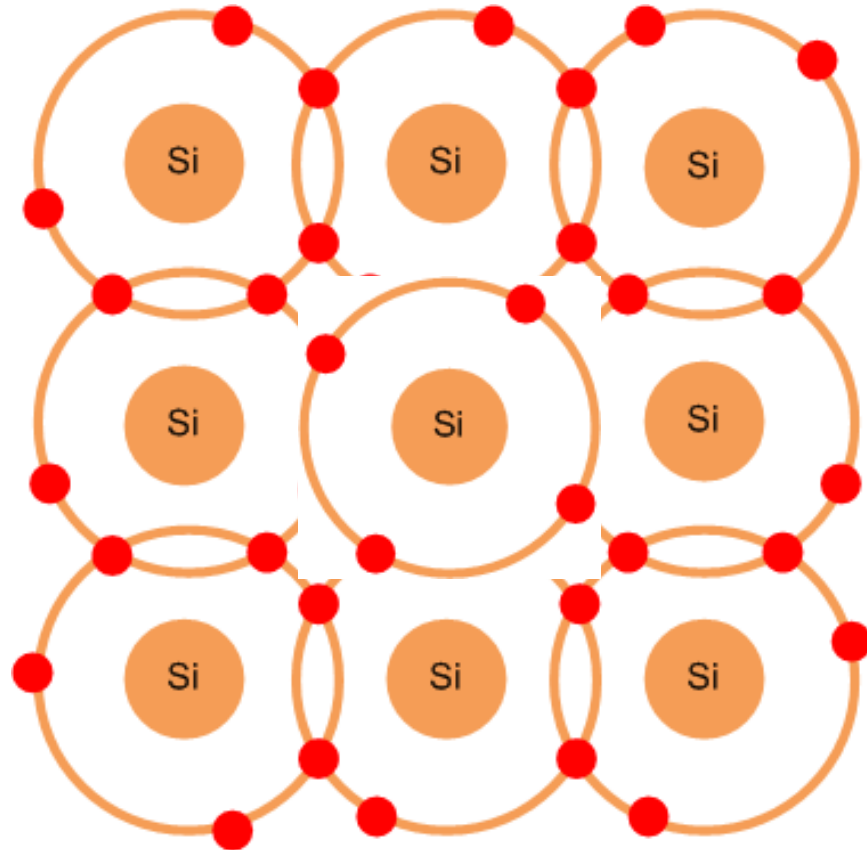


Relation : $E = (hc)/\lambda$ [eV]



2 eV \triangleq Si-Si Bondenergy

Releasing a Silicon Atom

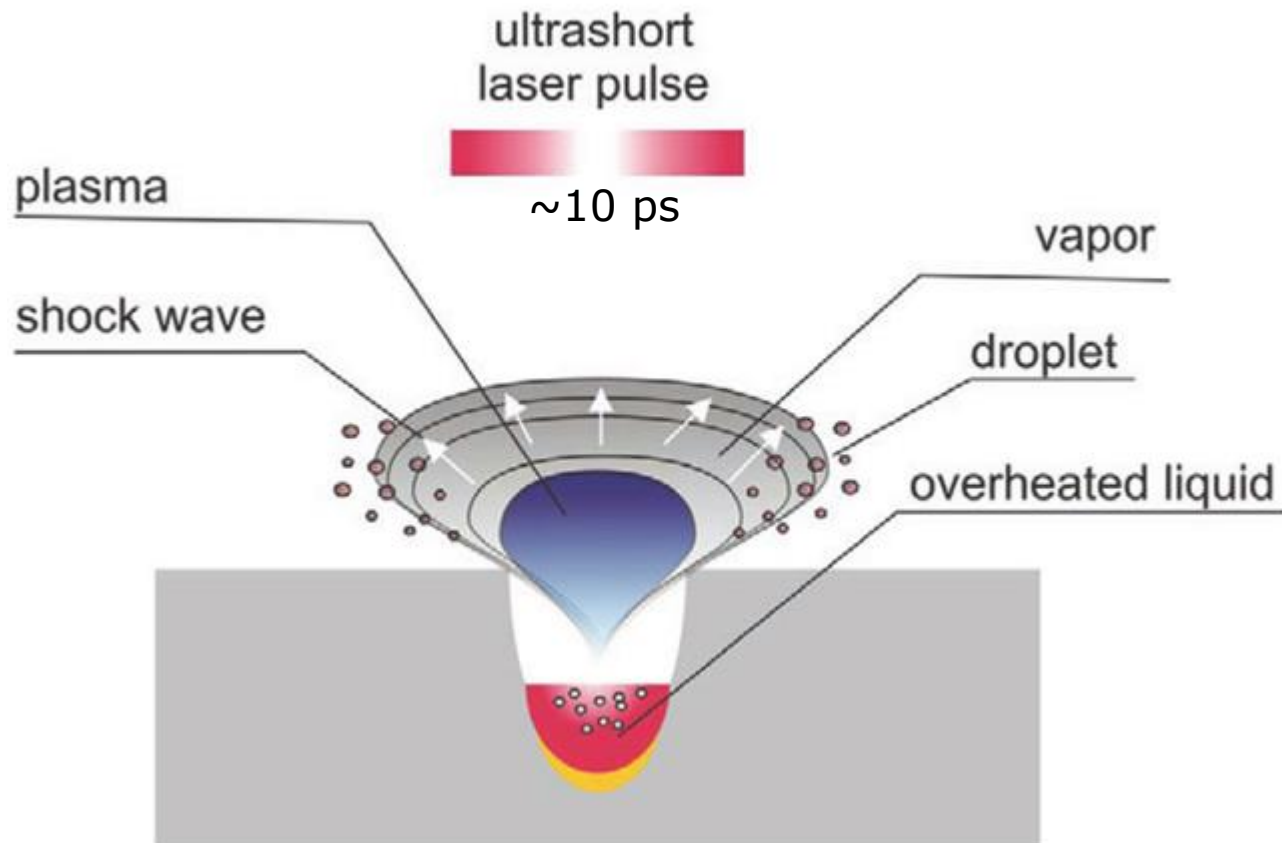


4 green photons

or

8 red photons

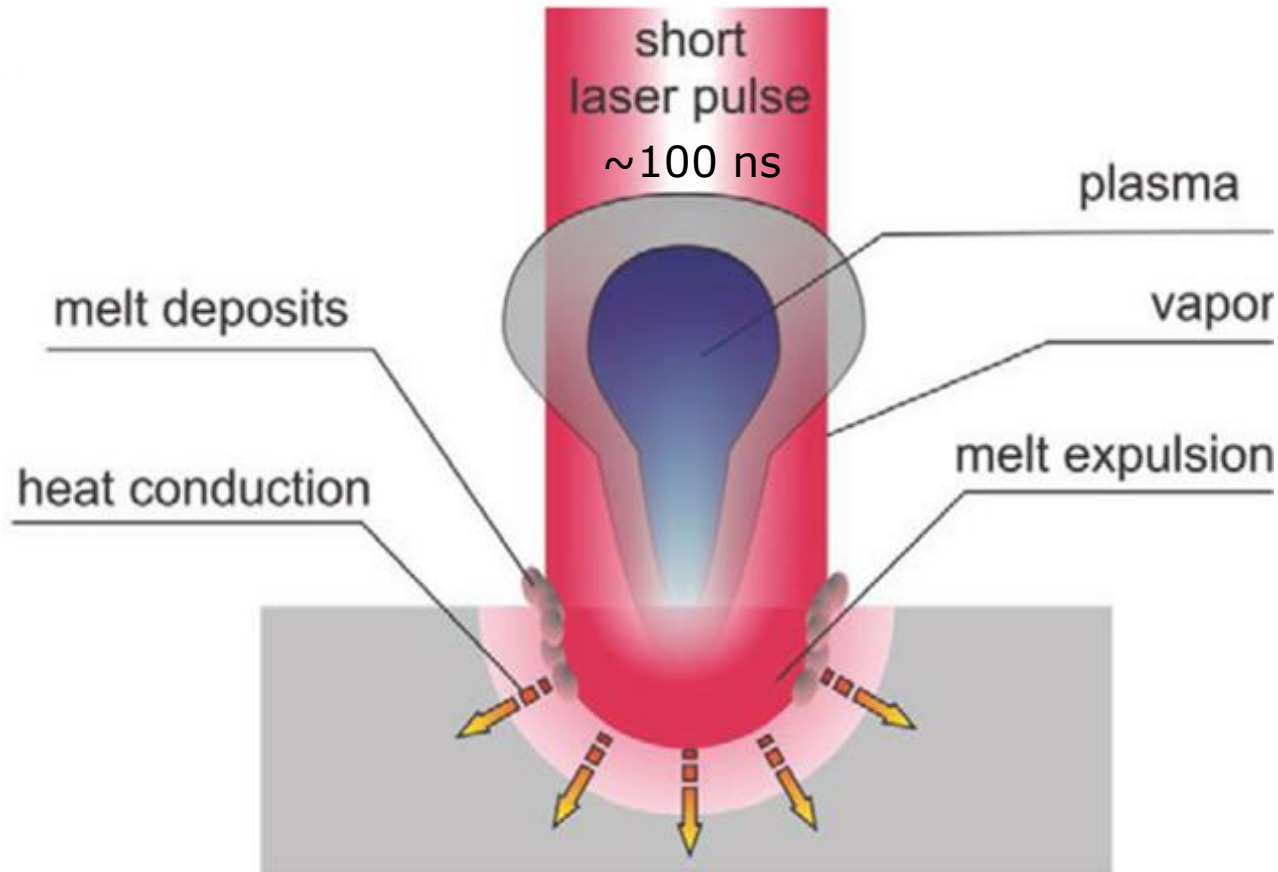
How does Laser machining work in principle?



Pulses by Pulse – layer by layer – material is removed.

No (less) debris → high precision process.

How does Laser machining work in principle?



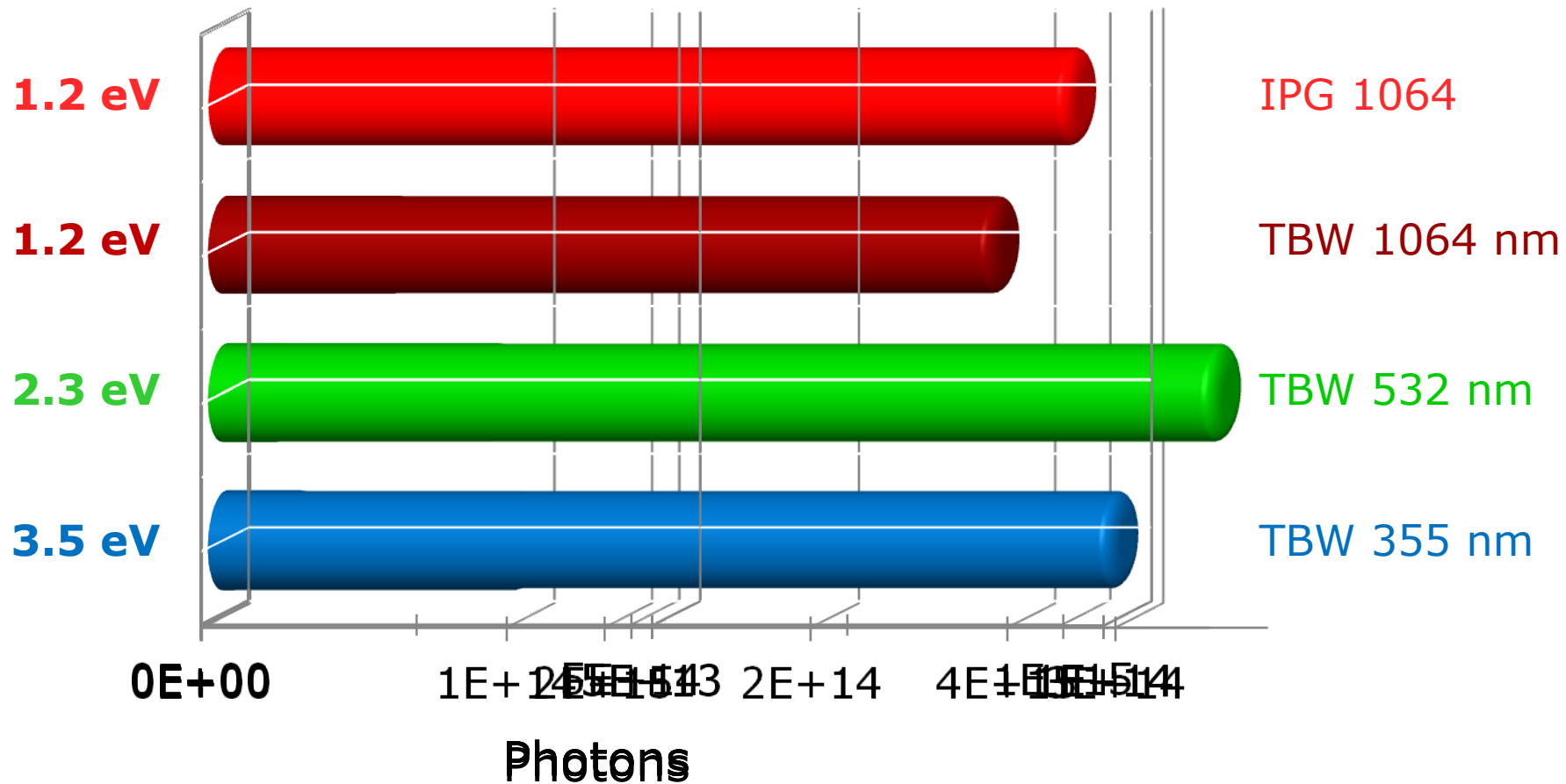
Pulses by Pulse – layer by layer – material is removed.

The cost of processing speed is quality.

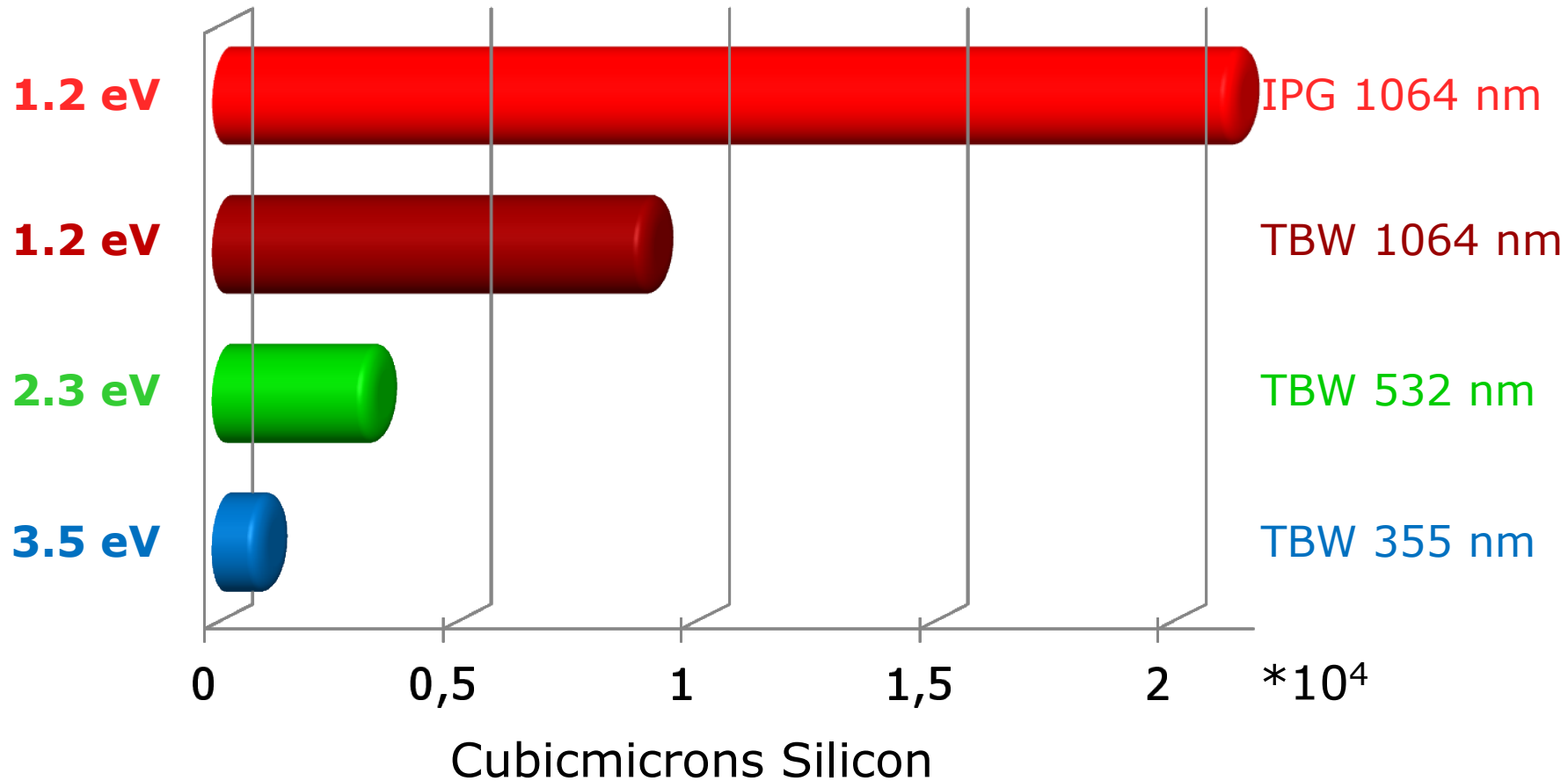
The Machine's Laser System

| Parameter | Unit | Min | Typ | Max |
|------------------|-------------|------------|------------|------------|
| Pulse duration | ps | 10.4 | ? | 105 000 |

The number of photons per pulse



Evaporated volume per pulse



10 ps laser pulse with 1 MHz repetition rate

Open your eyes for 1 second

Keep them closed for a day



10 ps laser pulse

8.3 minutes

Sun



How to envision a flux of 5.4 TW/cm²?

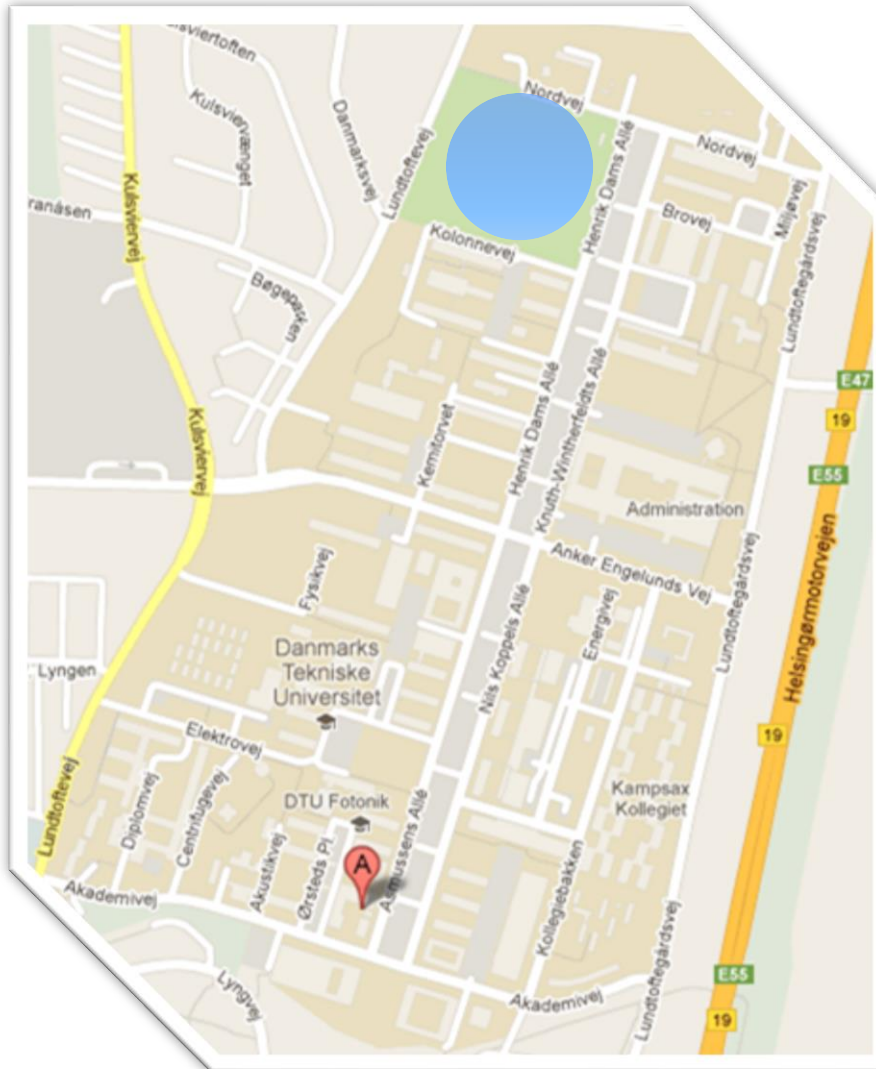


Lens = 20 cm

Spot = 20 μm

Spot = 2 mm

How to envision an irradiance of 5.4 TW/cm^2 ?



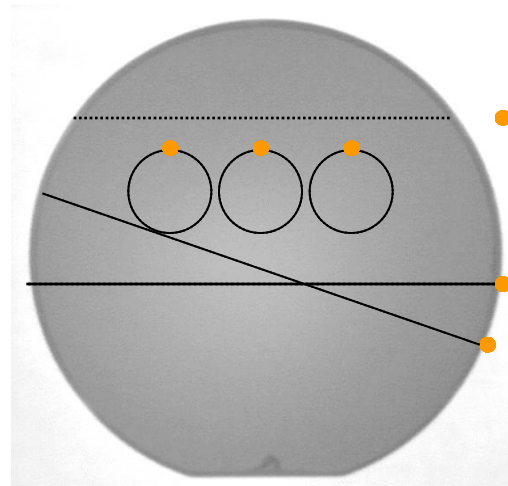
A lens of **200 meter** in diameter would be required!

How does Laser machining work in practice?

Dicing a Wafer

Laser–Material Interaction: **1 minute**

Iterations: **1000 times**



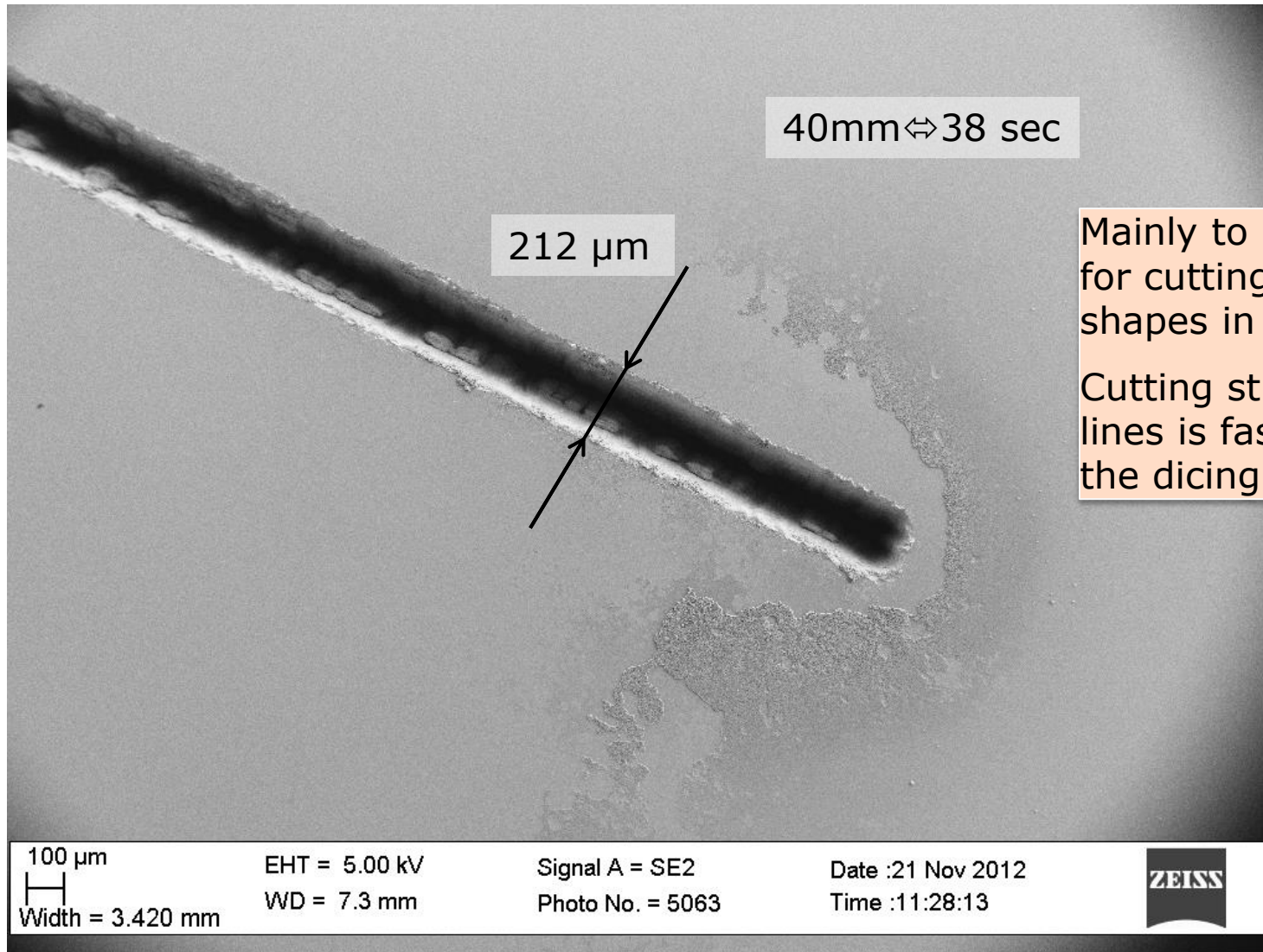
Scanspeed: **2000 mm/s**

10^7 pulses in total

Where can it used?

APPLICATIONS

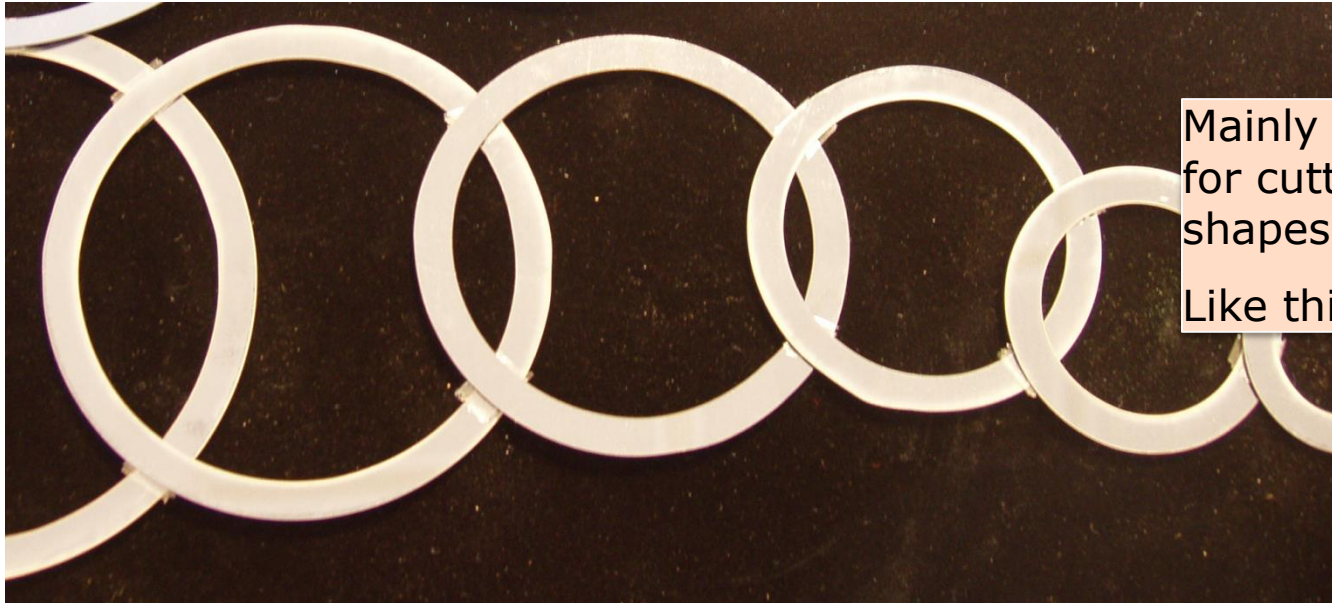
Dicing Silicon



Mainly to be used for cutting odd shapes in silicon.

Cutting straight lines is fast using the dicing saw

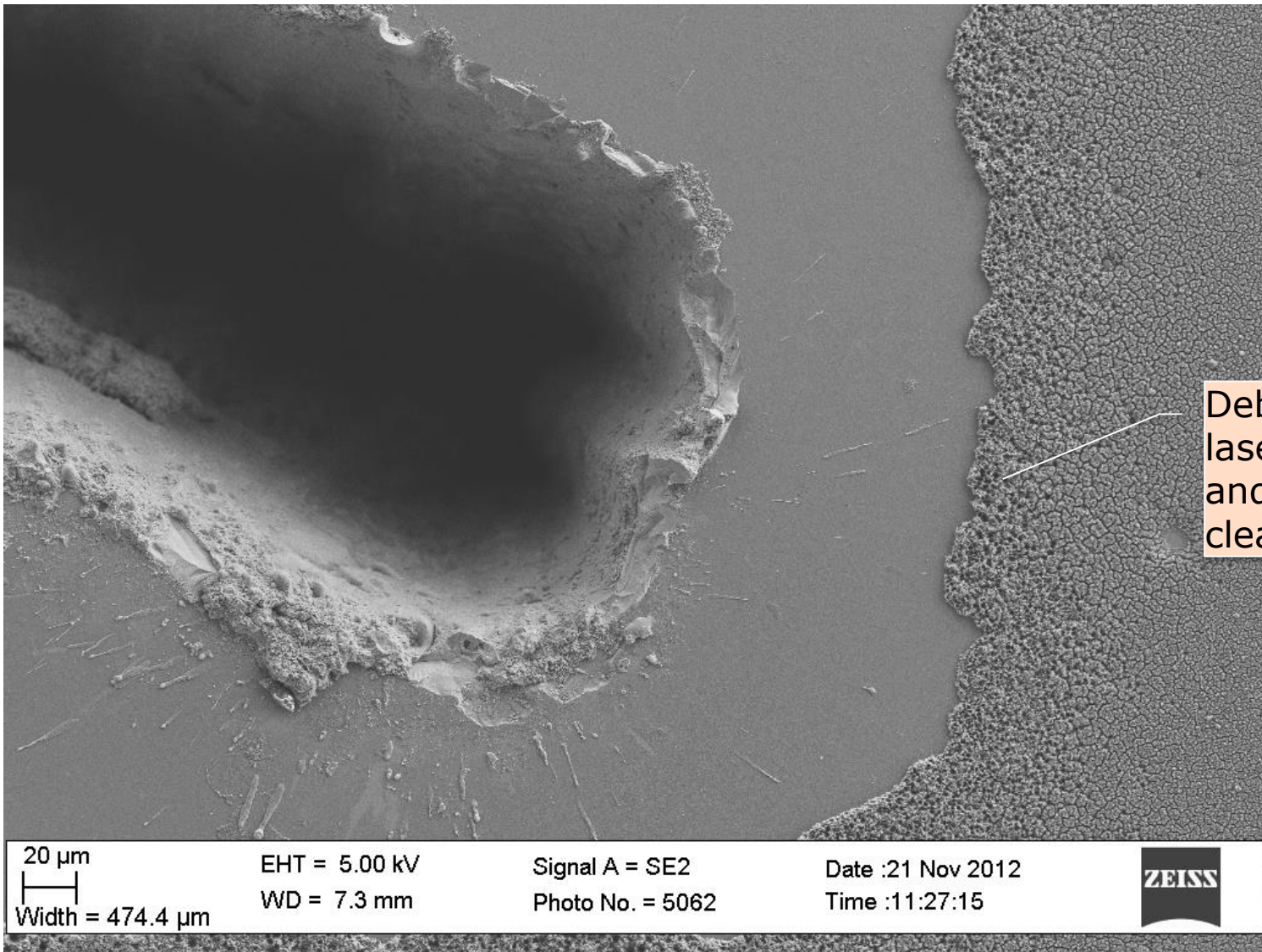
Dicing Silicon



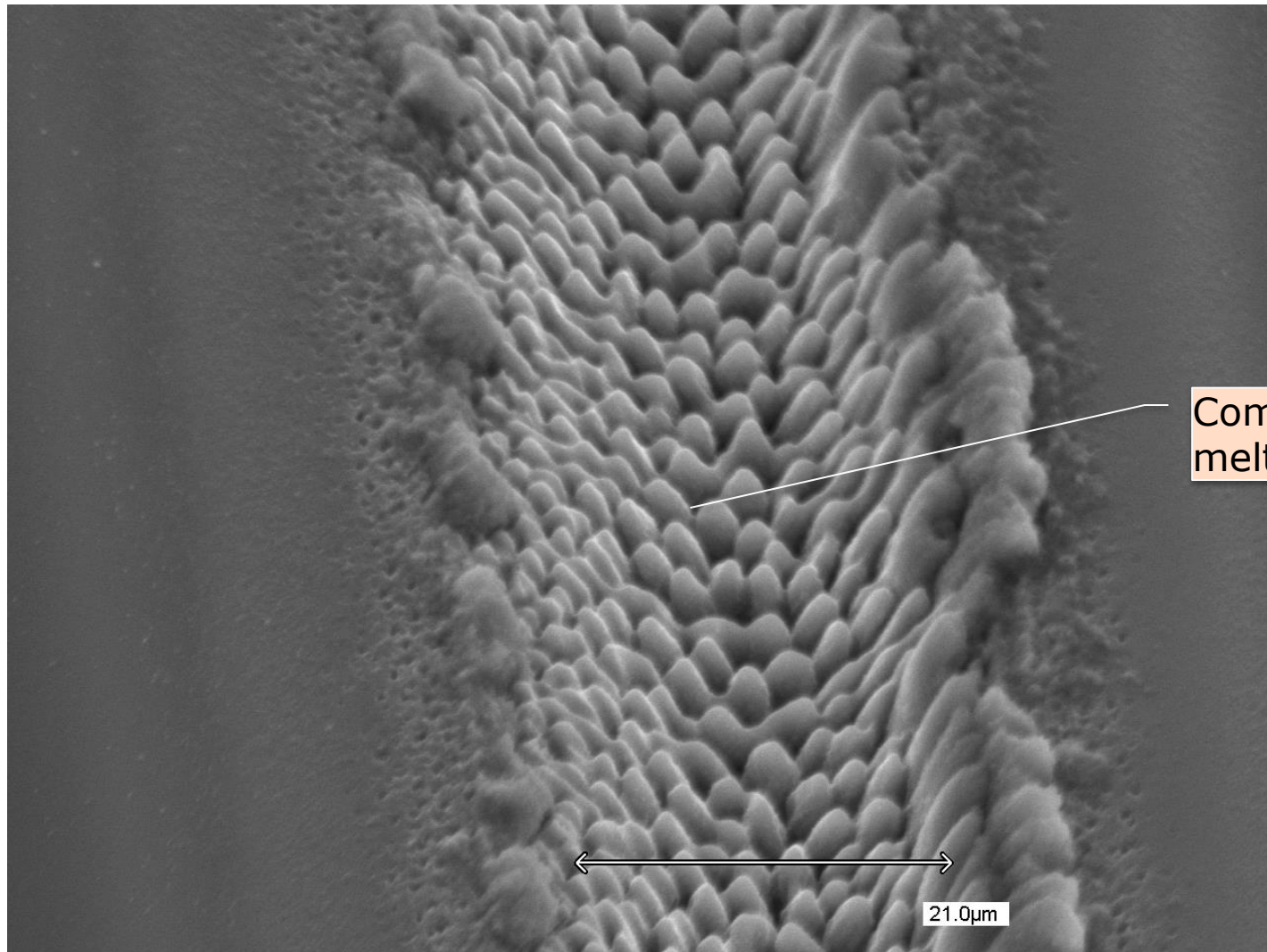
Mainly to be used
for cutting odd
shapes in silicon.

Like this...

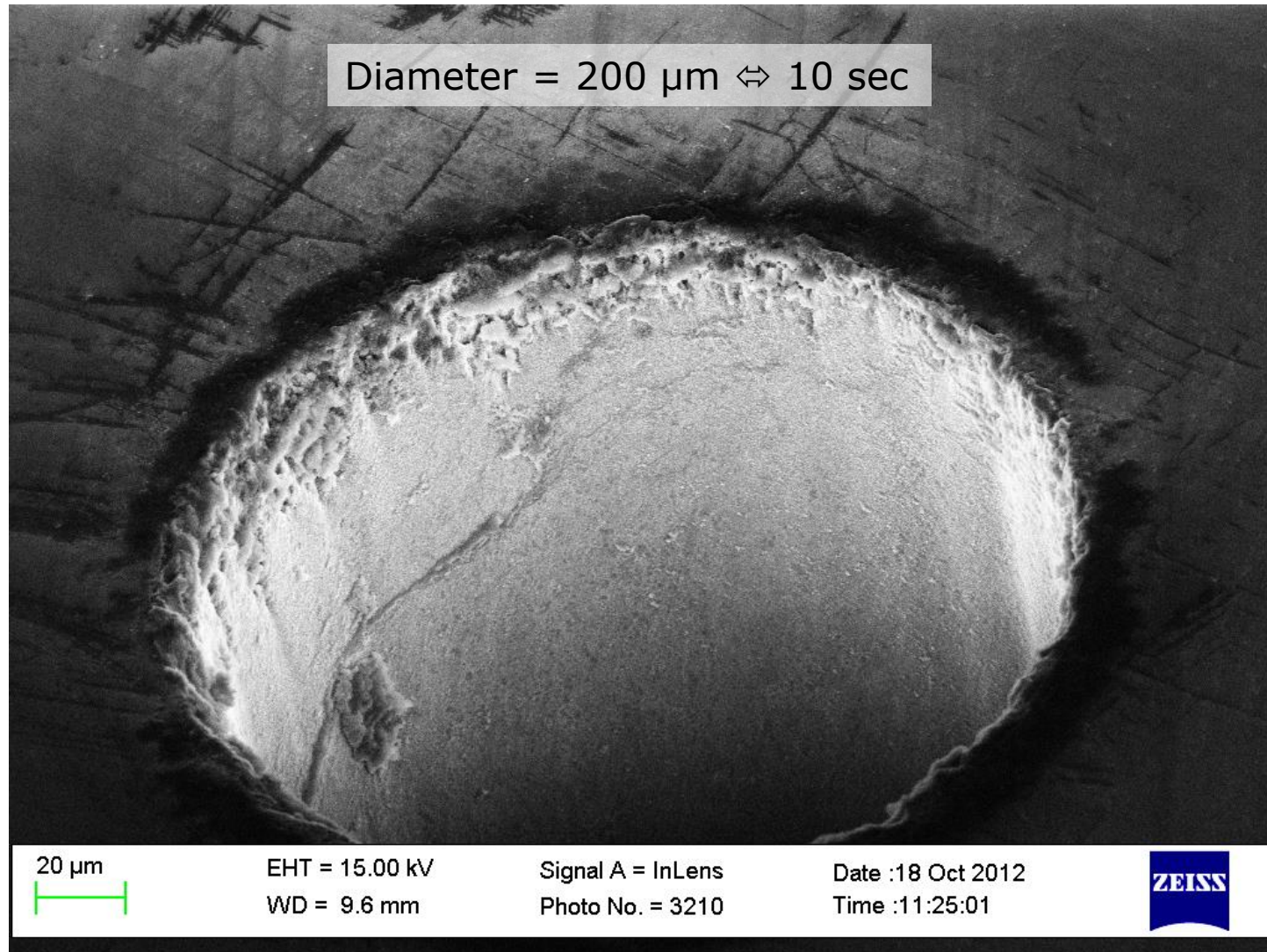
Dicing Silicon



Dicing Silicon



Hole Drilling in Silicon

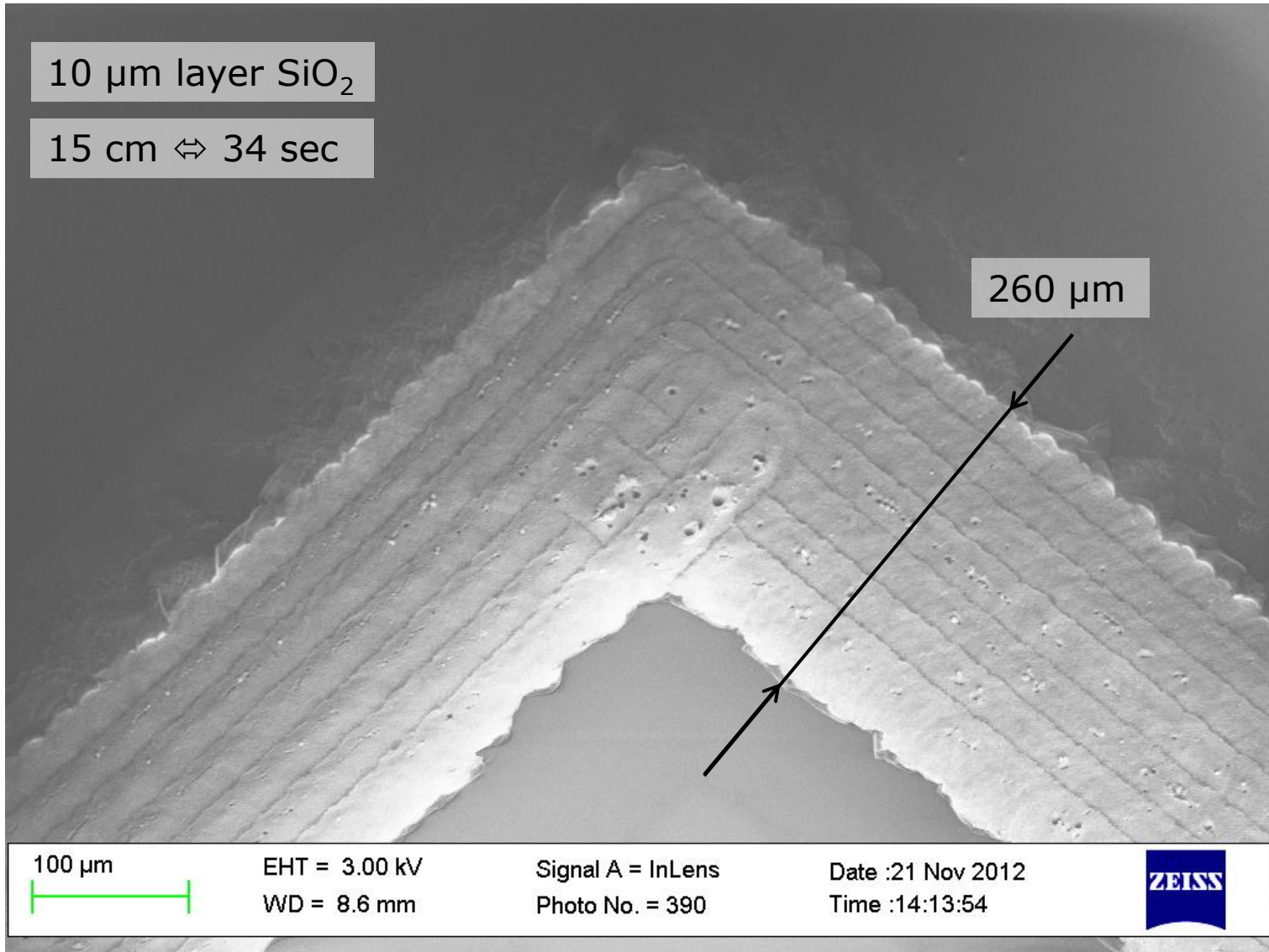


Dicing Silicondioxide (on silicon)

10 μm layer SiO_2

15 cm \Leftrightarrow 34 sec

260 μm



100 μm

EHT = 3.00 kV

Signal A = InLens

Date :21 Nov 2012

WD = 8.6 mm

Photo No. = 390

Time :14:13:54

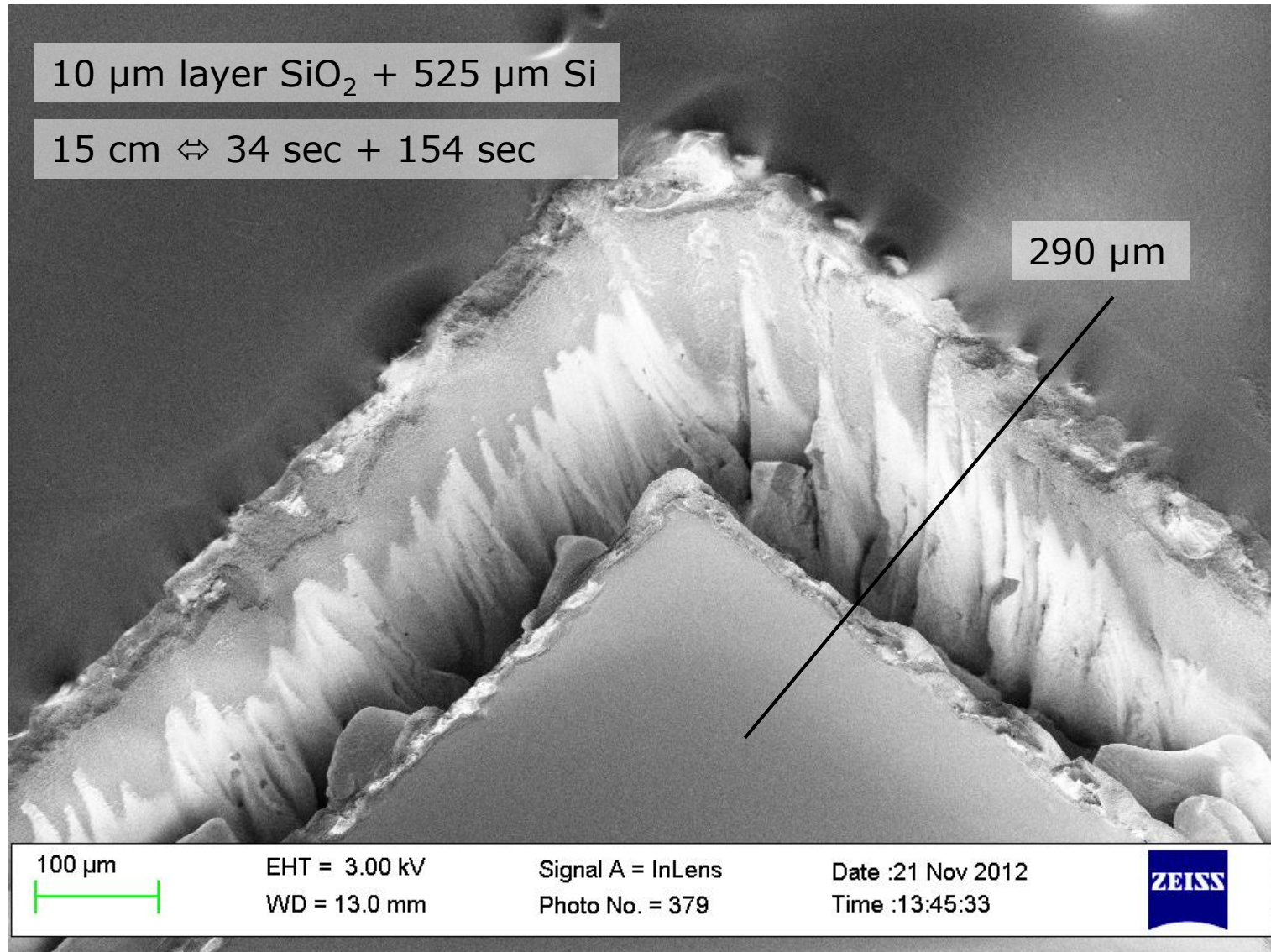


Dicing Silicondioxide and Silicon

10 μm layer SiO_2 + 525 μm Si

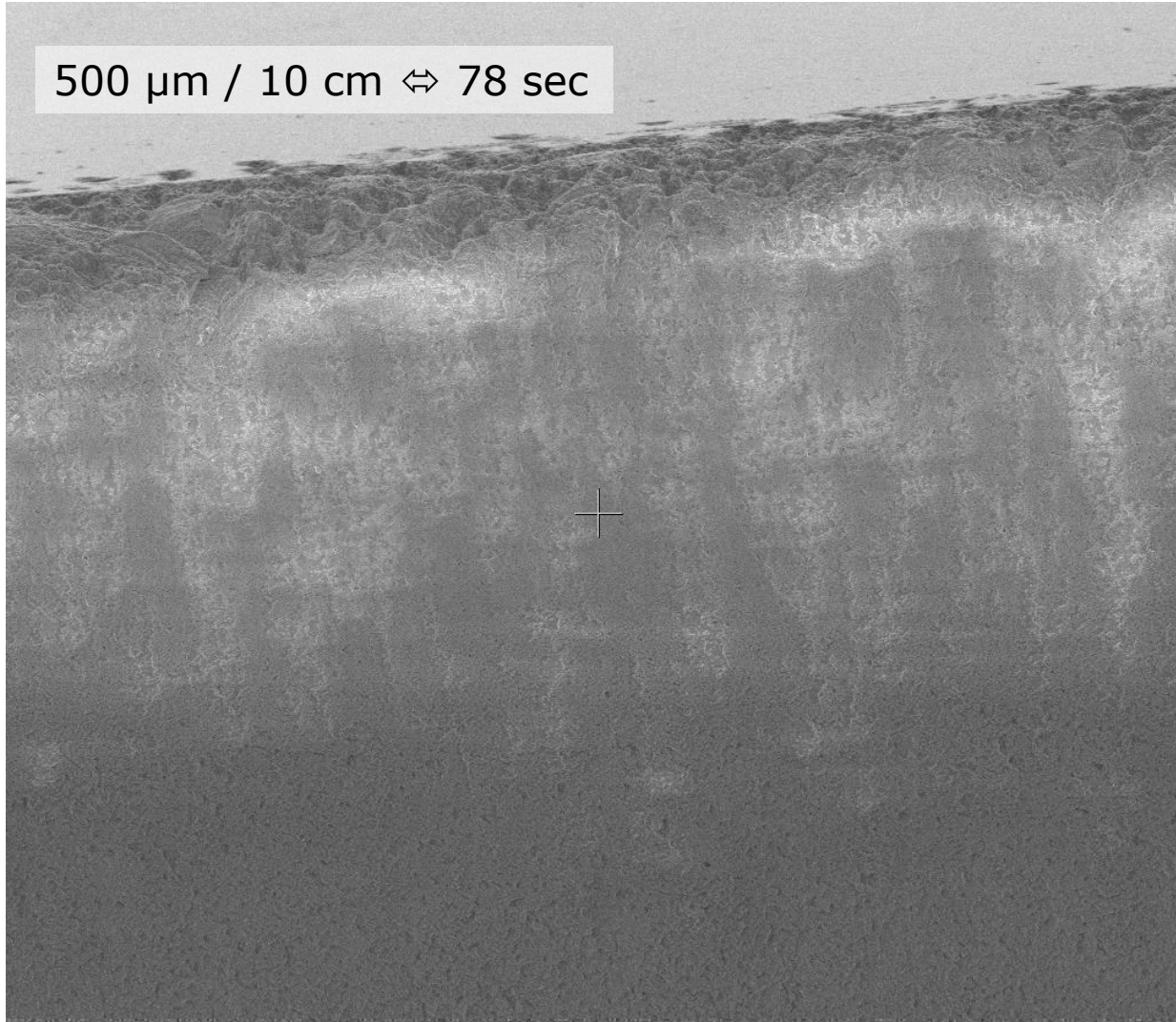
15 cm \Leftrightarrow 34 sec + 154 sec

290 μm



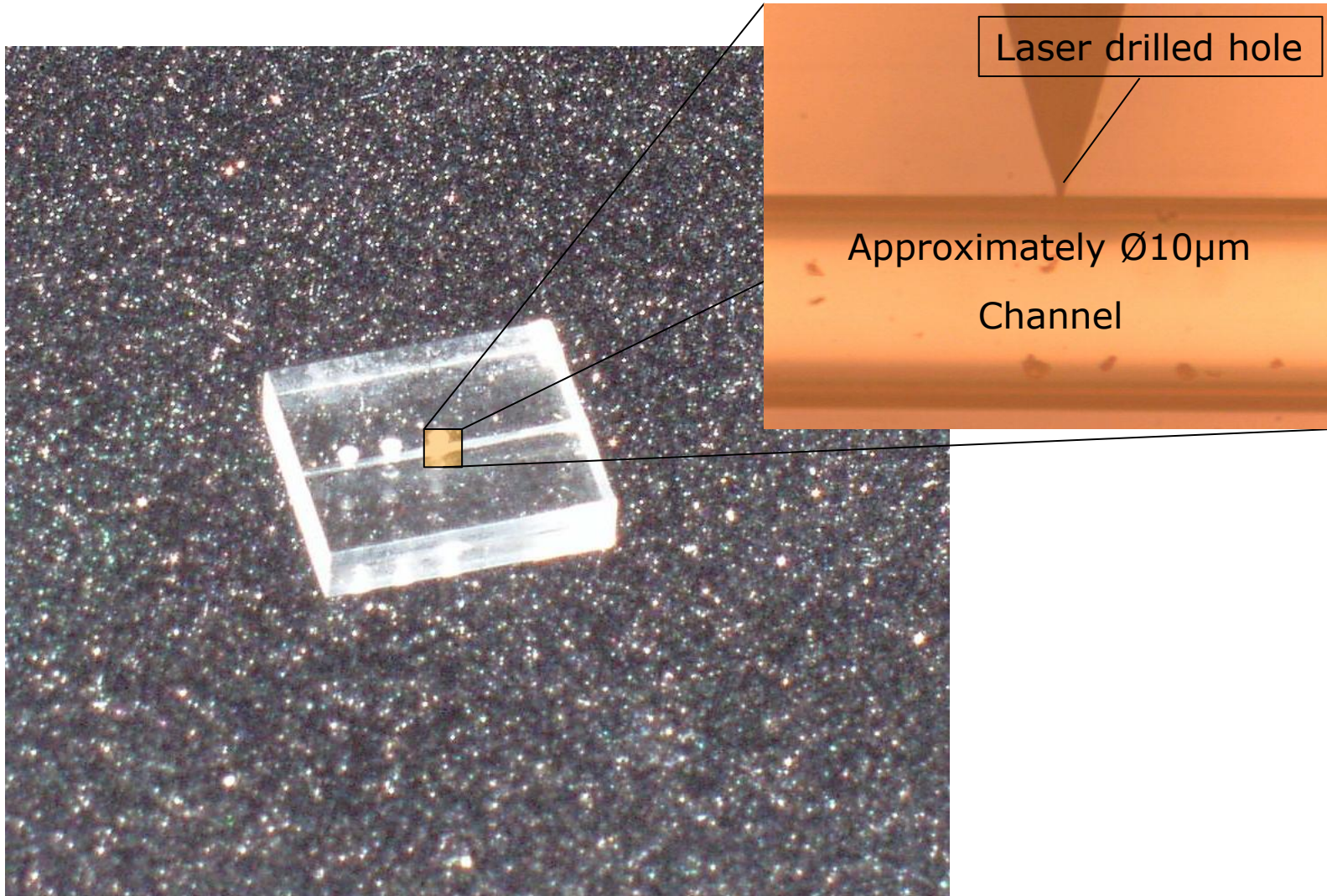
Dicing Fused Silica

500 μm / 10 cm \leftrightarrow 78 sec

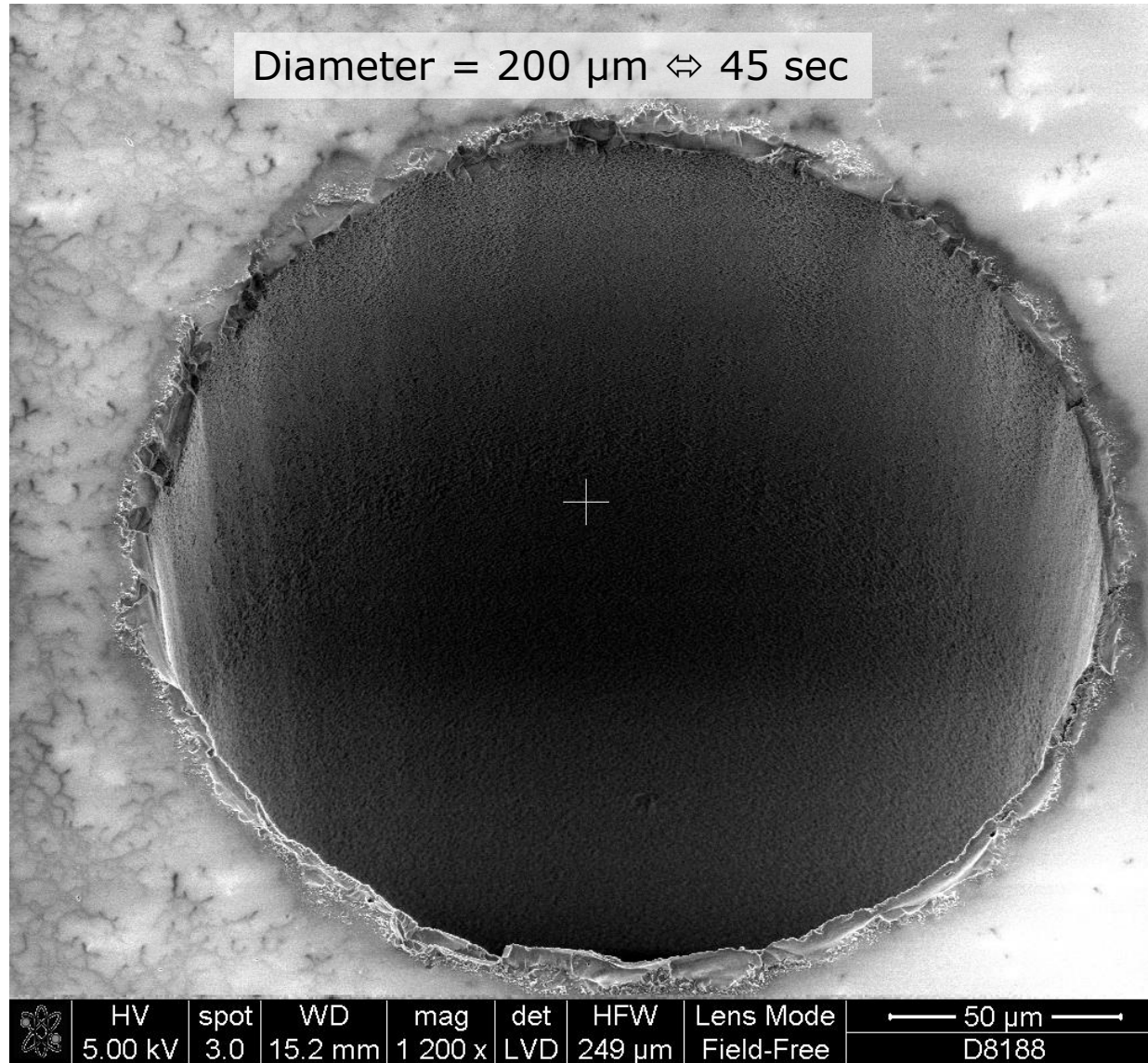


| | | | | | | | | |
|---|---------|------|---------|-------|-----|-------------------|------------|-------------------------------|
|  | HV | spot | WD | mag | det | HFW | Lens Mode | ← 50 μm → D8188 |
| | 3.00 kV | 3.0 | 12.1 mm | 446 x | LVD | 335 μm | Field-Free | |

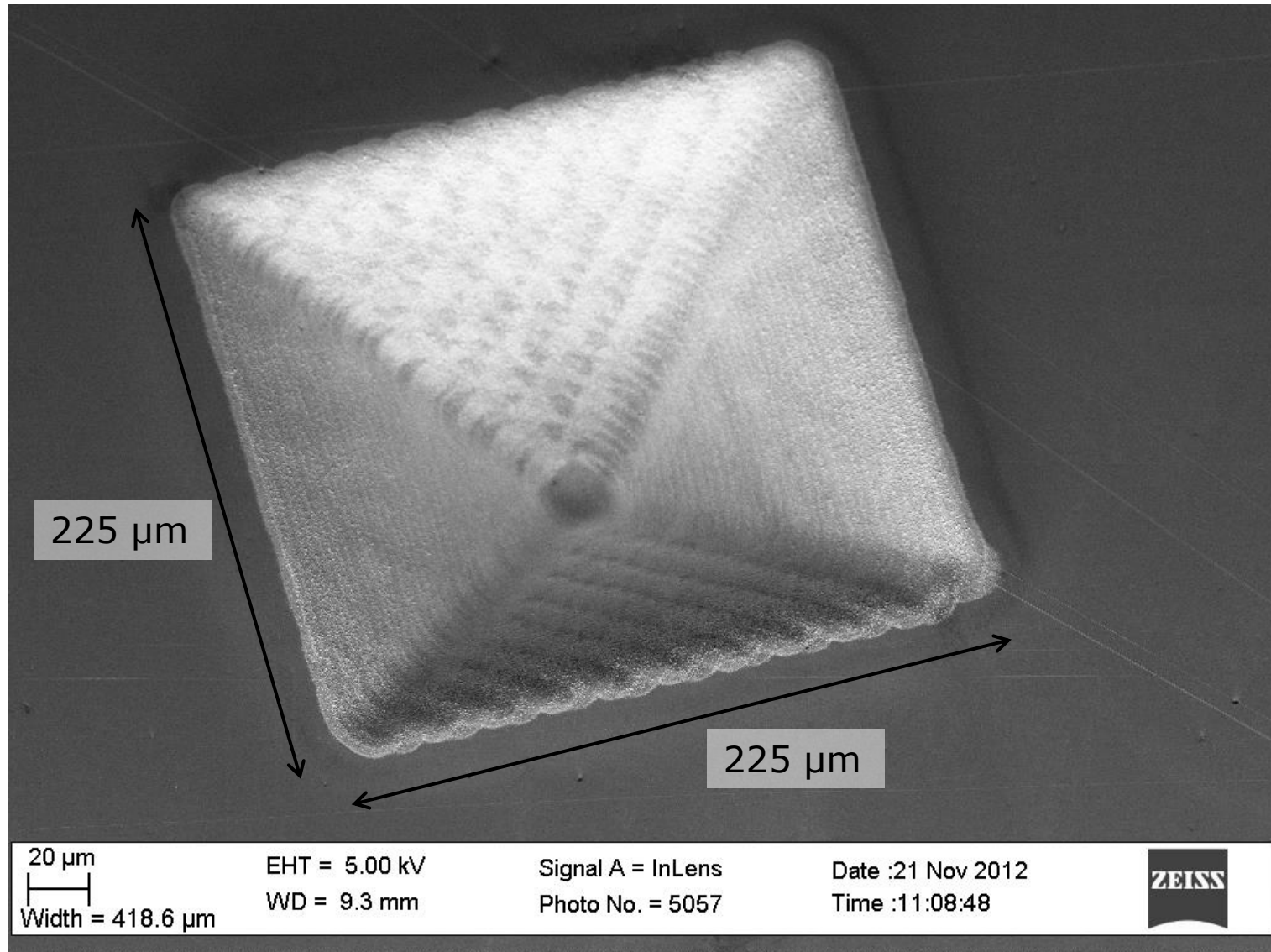
Drilling very small holes in borofloat glass



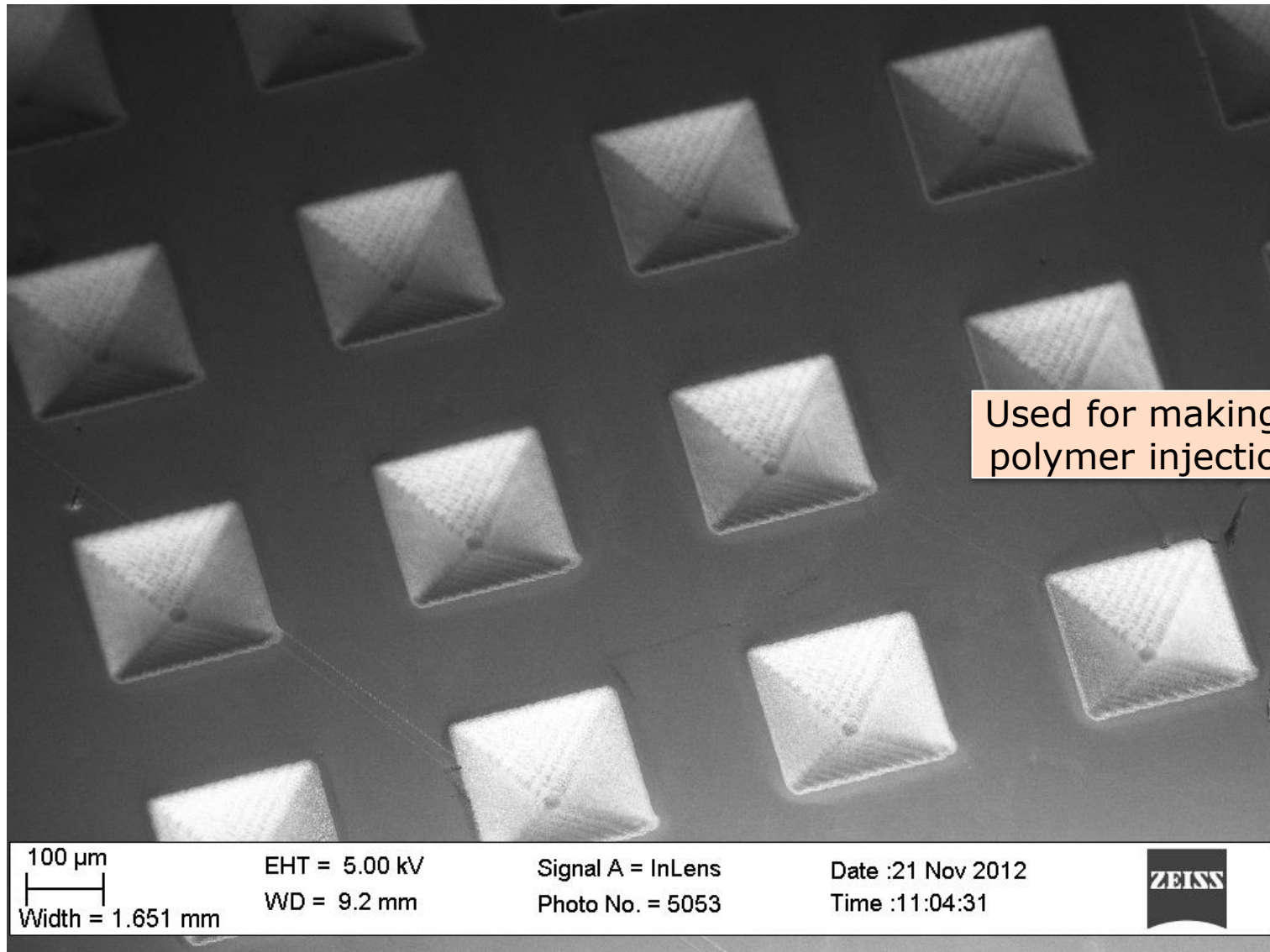
Larger holes in Borofloat



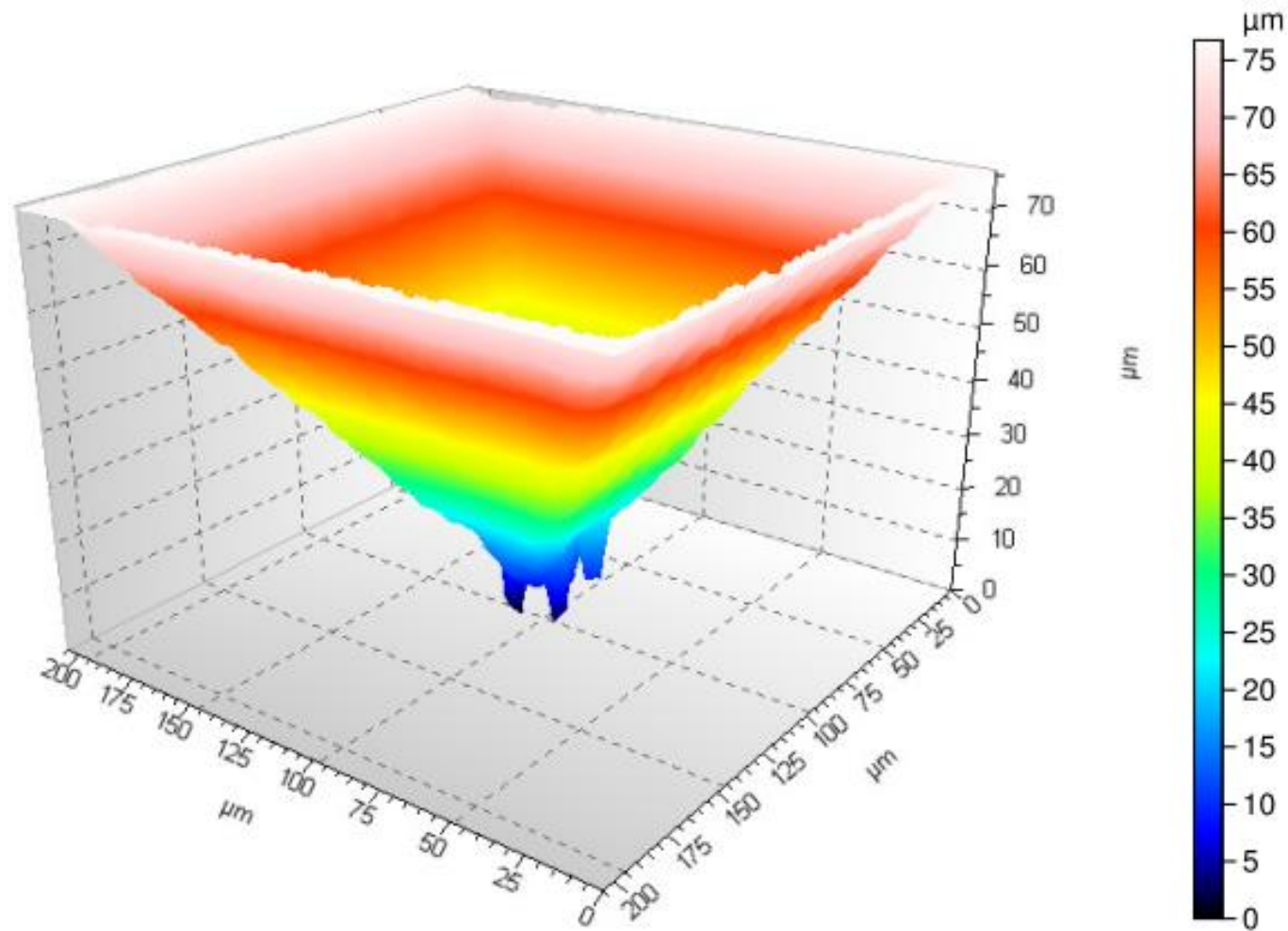
3D Microstructuring of Nickel



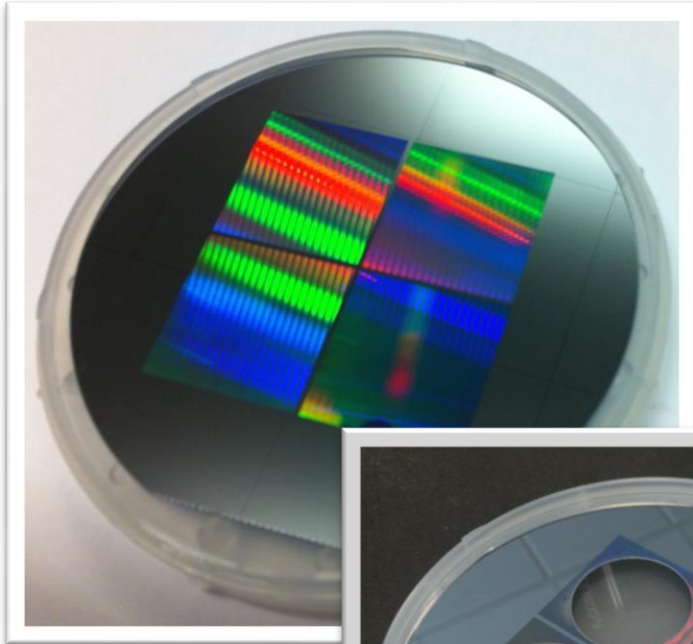
3D Microstructuring of Nickel



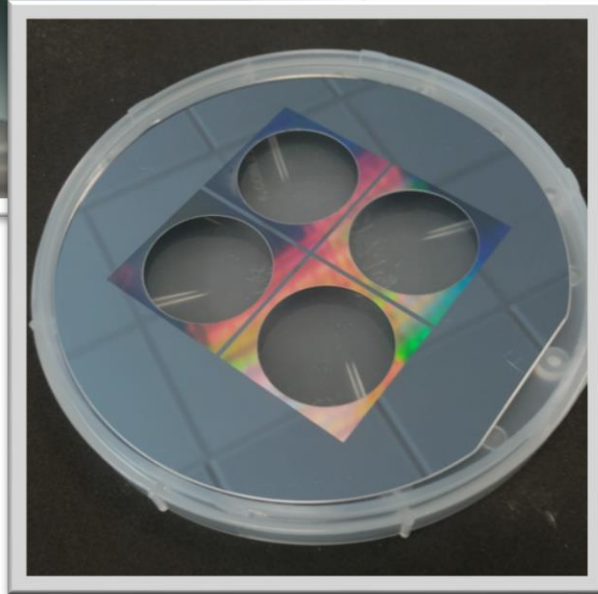
Microstructuring Nickel



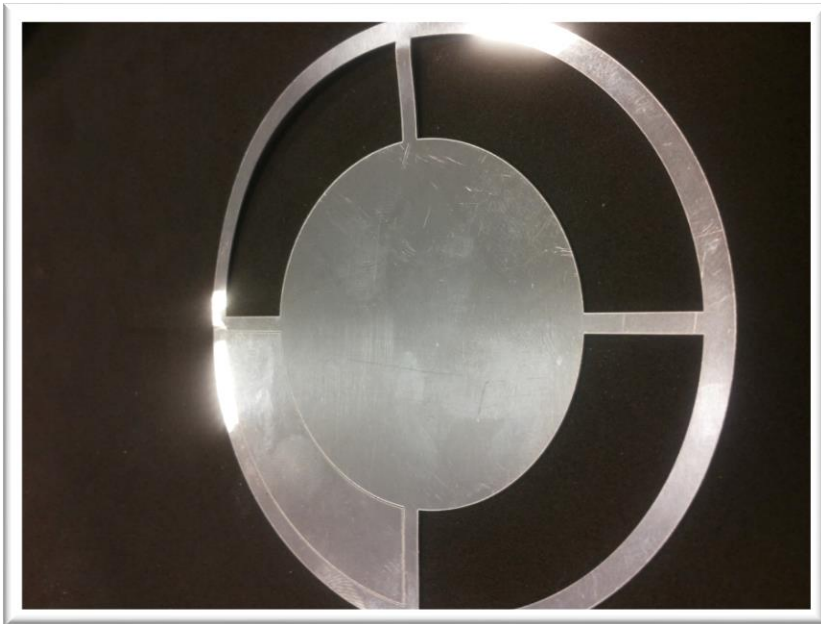
Dicing patterned silicon



Customer : René Bergmann



Shadow mask



Customer : Anil Haraksingh Thilsted

400 μ m thick aluminum

TEM holder for nitride membrane

Customer : Eric Jensen

Using the Laser Micromachining tool at Danchip

PRACTICAL INFORMATION

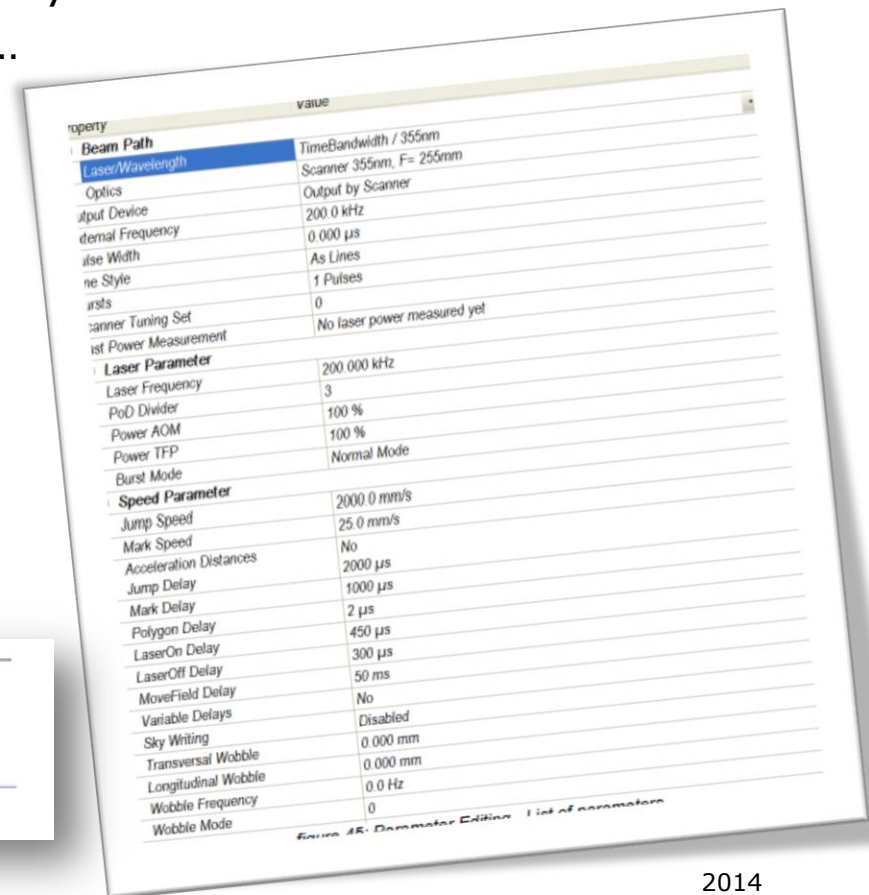
Sign up for training

- Write to training@danchip.dtu.dk
- Please describe what you want to do
 - Material
 - Dimensions
 - Cutting, milling or drilling holes?
 - If possible enclose drawing
- Training requires 2 sessions of approximately 2 hours



Processing parameters

- We have some basic knowledge/experience on processing parameters for some materials
- Process optimization is your responsibility
 - but we would appreciate feedback...
- Many parameters to optimize on...
 - Power
 - Writing speed
 - Repetition frequency
 - Pulse burst mode/picking
 - Iterations
 - Focus
 - ...



| property | value |
|------------------------|-----------------------------|
| Beam Path | TimeBandwidth / 355nm |
| Laser/Wavelength | Scanner 355nm, F= 255mm |
| Optics | Output by Scanner |
| Output Device | 200.0 kHz |
| External Frequency | 0.000 µs |
| Pulse Width | As Lines |
| Line Style | 1 Pulses |
| Starts | 0 |
| Scanner Tuning Set | No laser power measured yet |
| 1st Power Measurement | |
| Laser Parameter | 200.000 kHz |
| Laser Frequency | 3 |
| PoD Divider | 100 % |
| Power AOM | 100 % |
| Power TFP | Normal Mode |
| Burst Mode | |
| Speed Parameter | 2000.0 mm/s |
| Jump Speed | 25.0 mm/s |
| Mark Speed | No |
| Acceleration Distances | 2000 µs |
| Jump Delay | 1000 µs |
| Mark Delay | 2 µs |
| Polygon Delay | 450 µs |
| LaserOn Delay | 300 µs |
| LaserOff Delay | 50 ms |
| MoveField Delay | No |
| Variable Delays | Disabled |
| Sky Writing | 0.000 mm |
| Transversal Wobble | 0.000 mm |
| Longitudinal Wobble | 0.0 Hz |
| Wobble Frequency | 0 |
| Wobble Mode | |

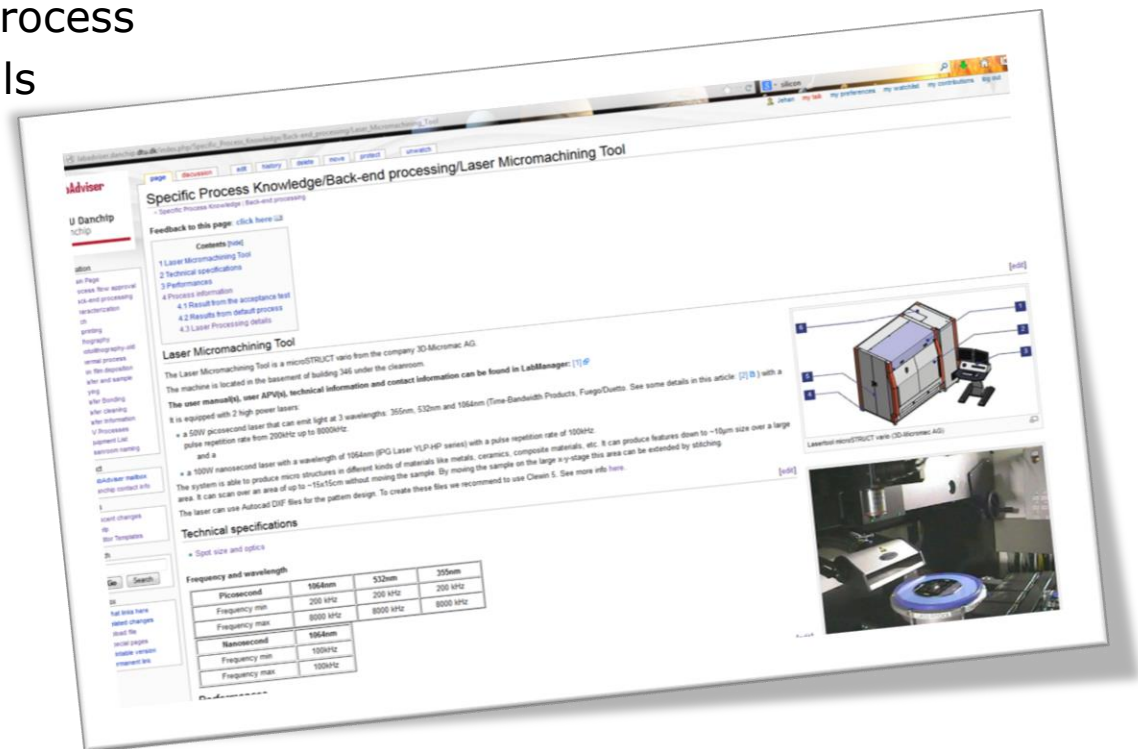
Figure 45: Parameter Editor - List of parameters



Information on LabAdviser

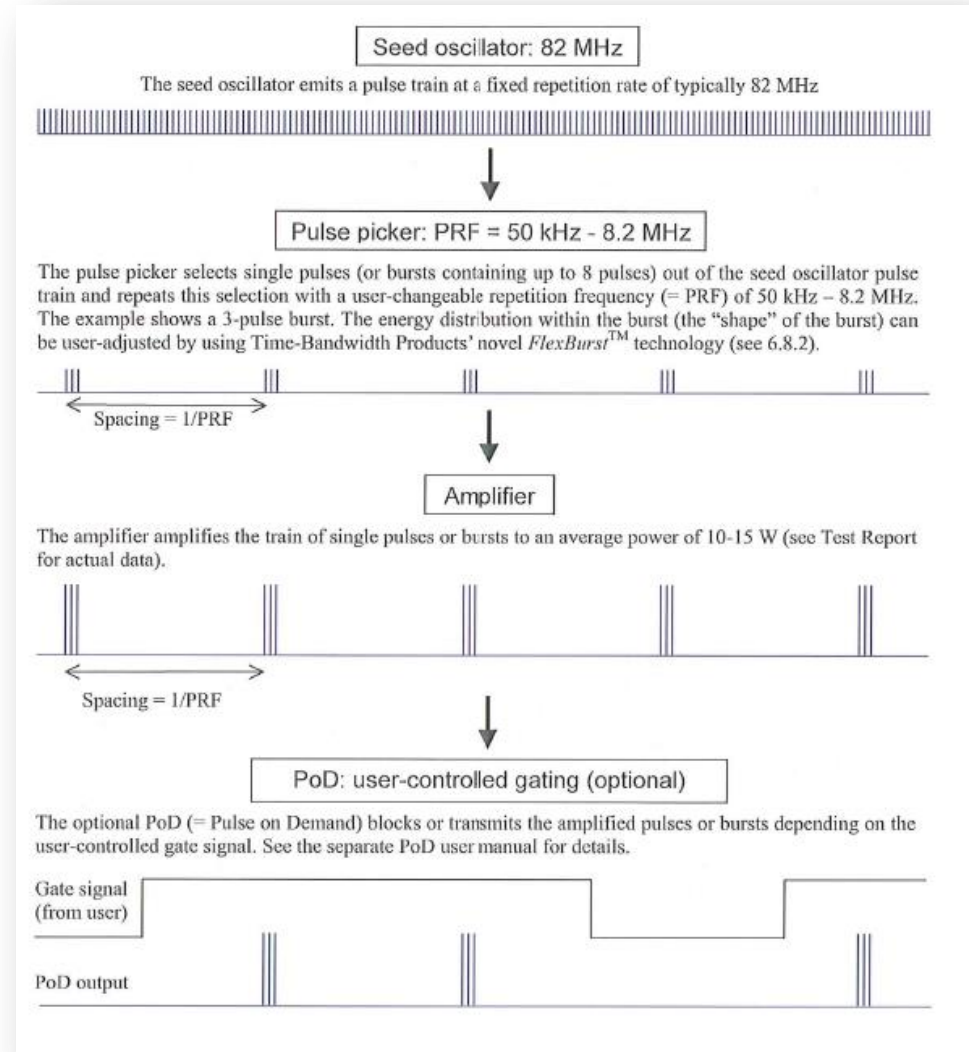
- Technical specifications
- Performance
- Process information
 - Result from the acceptance test
 - Results from default process
 - Laser Processing details

Find it under:
 Back-end processing/
 Laser Micromachining Tool



Picosecond Laser operation

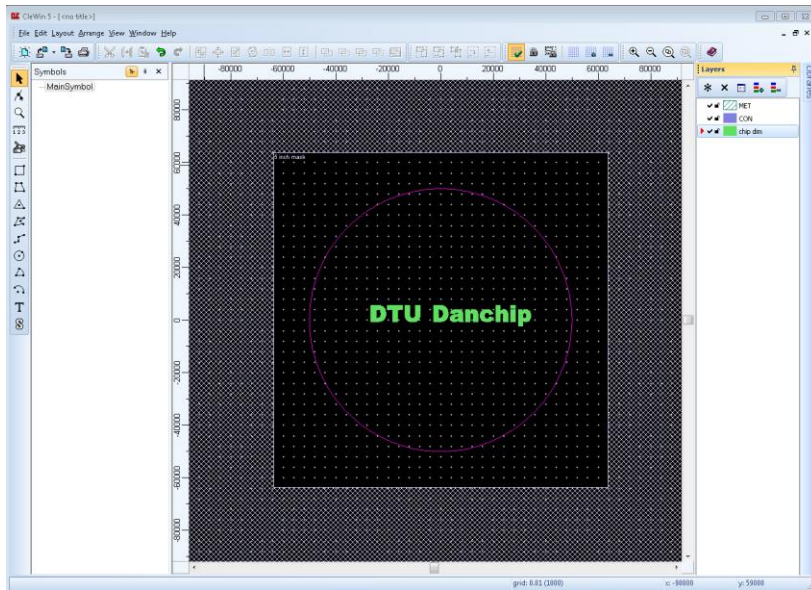
- Time Bandwidth – Duetto



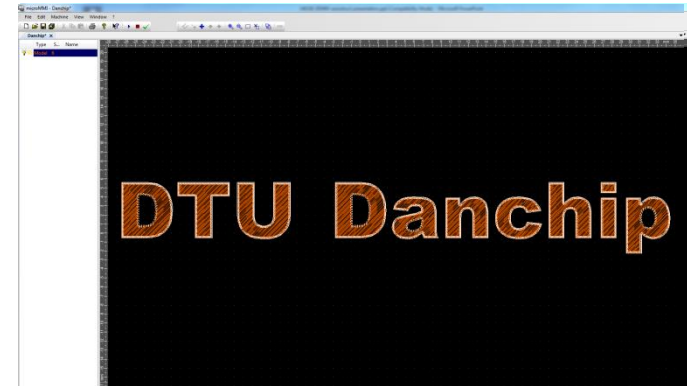
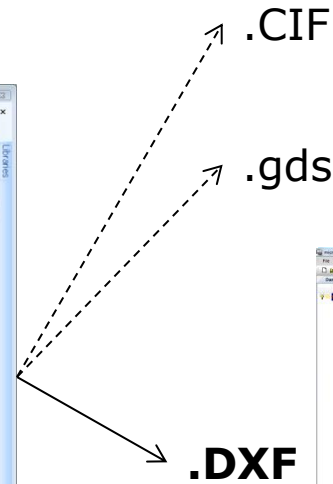
How to design a pattern ?

DESIGN

Design graphical pattern for laser software



CleWin 5.1 - interface

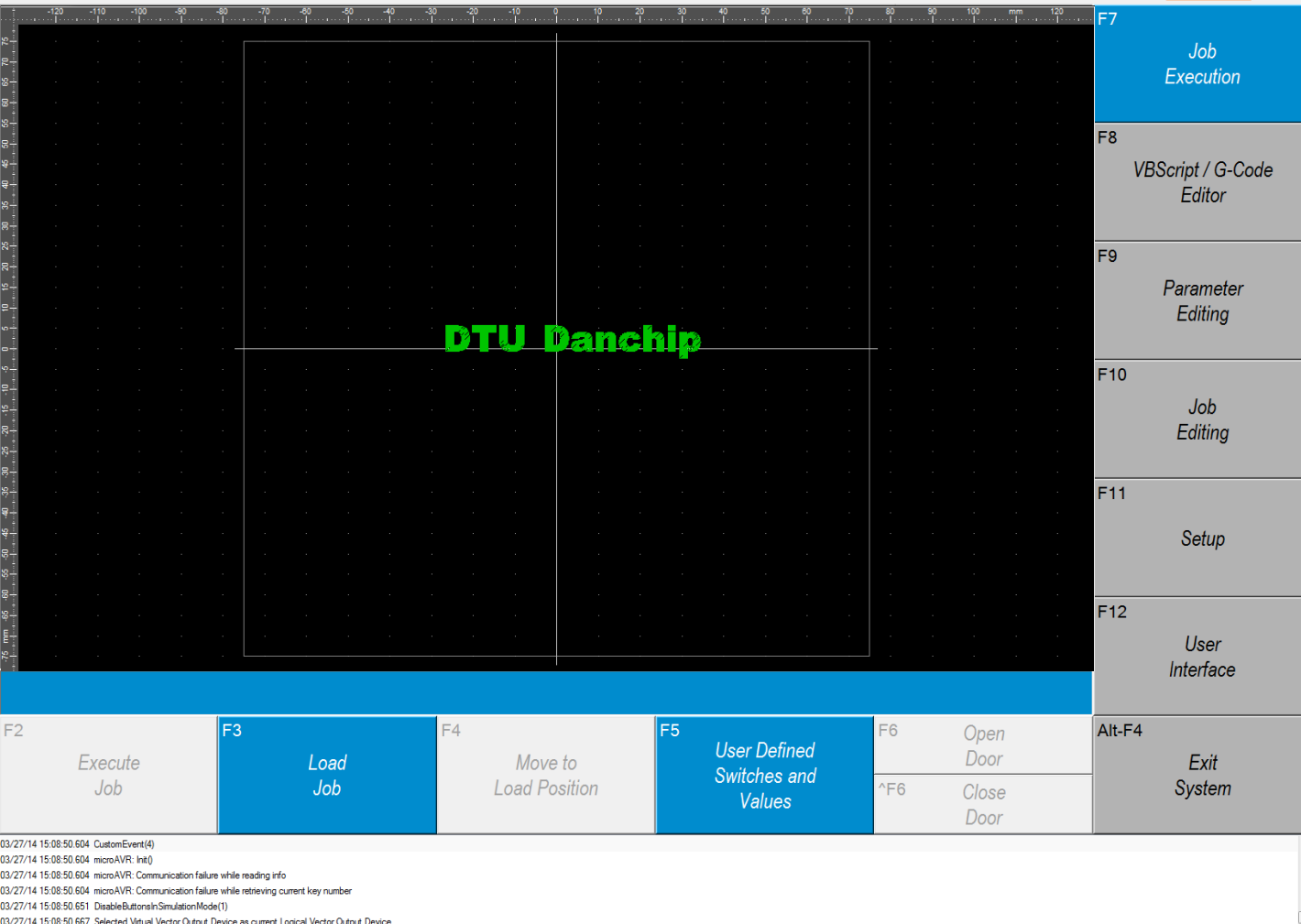


microMMI - interface software

.CONX

Design graphical pattern for laser software

microSTRUCT Vario - Job Execution MICROMAC



DTU Danchip

| | | | | | | |
|--------------------------|----------------|-----------------------------|--|-------------------|-----------------------|-----|
| Job Execution | | | | | | F7 |
| VBScript / G-Code Editor | | | | | | F8 |
| Parameter Editing | | | | | | F9 |
| Job Editing | | | | | | F10 |
| Setup | | | | | | F11 |
| User Interface | | | | | | F12 |
| F2 Execute Job | F3 Load Job | F4 Move to Load Position | F5 User Defined Switches and Values | F6 Open Door | Alt-F4 Exit System | |
| | | | | ^F6 Close Door | | |

```

03/27/14 15:08:50.604 CustomEvent(4)
03/27/14 15:08:50.604 microAVR: Init()
03/27/14 15:08:50.604 microAVR: Communication failure while reading info
03/27/14 15:08:50.604 microAVR: Communication failure while retrieving current key number
03/27/14 15:08:50.651 DisableButtonsInSimulationMode(1)
03/27/14 15:08:50.667 Selected Virtual Vector Output Device as current Logical Vector Output Device
  
```

microMMI Automation- interface

Design script pattern for laser software

microSTRUCT Vario - VBScript Editor

| | | | | | | |
|---------------------|---------------|---------------------|-----------------------|----|--------|--------------------------|
| F7 | | | | | | Job Execution |
| F8 | | | | | | VBScript / G-Code Editor |
| F9 | | | | | | Parameter Editing |
| F10 | | | | | | Job Editing |
| F11 | | | | | | Setup |
| F12 | | | | | | User Interface |
| F2 | F3 | F4 | F5 | F6 | Alt-F4 | |
| Create new VBScript | Load VBScript | Save VBScript | Toggle Editor/Preview | | Back | |
| | | Save VBScript as... | | | | |